

# SuperKEKB 入射器の現状報告 2019c(Phase3.2)～2020a(Phase3.3)

2020.4.8

第117回 Bファクトリー計画推進委員会  
加速器研究施設 飯田 直子

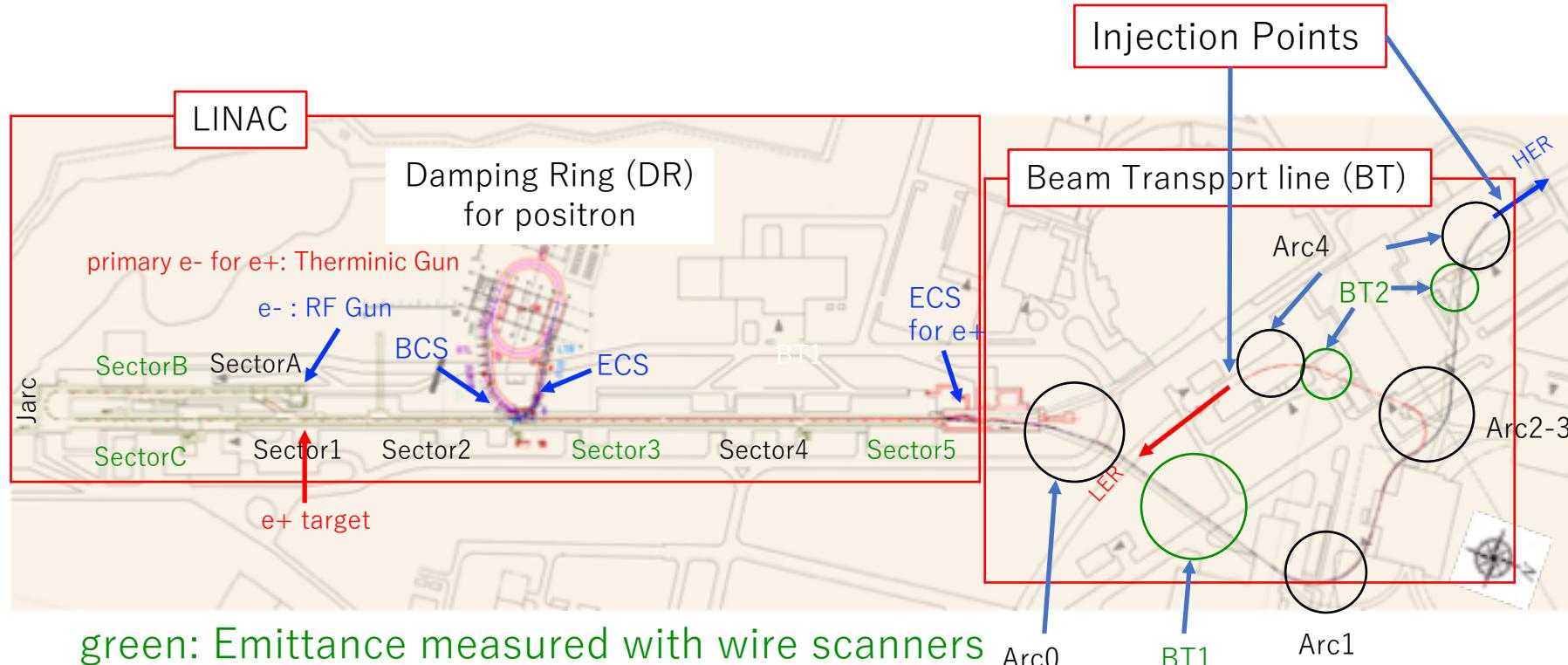
# Layout of LINAC, BT, Injection to MR

e+ beam injects into LER via DR:

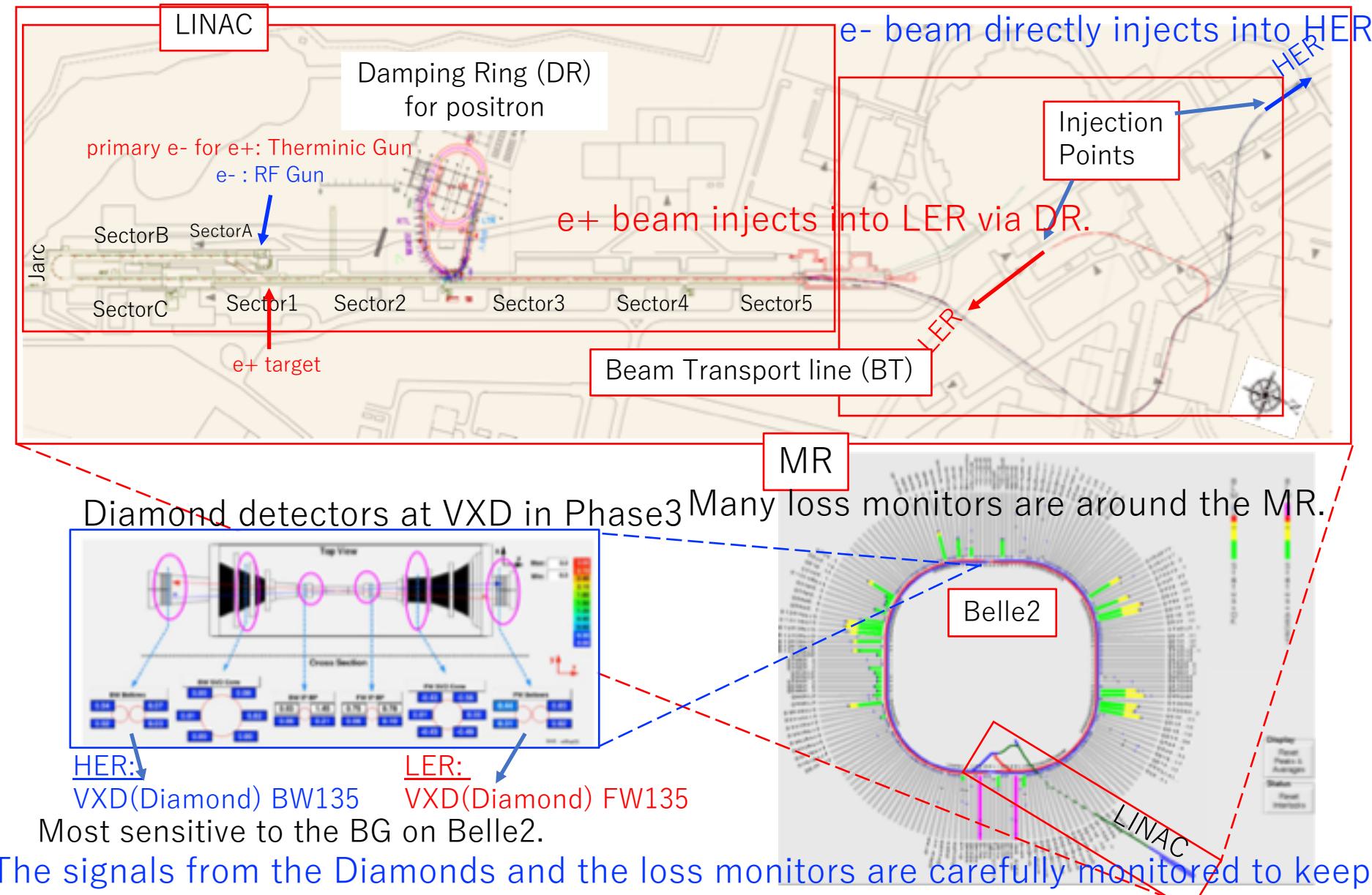
The injection BG is not affected very much by the condition upstream the DR.

e- beam directly injects into HER:

The injection BG is directly affected by the condition of RF-gun LINAC and BT.

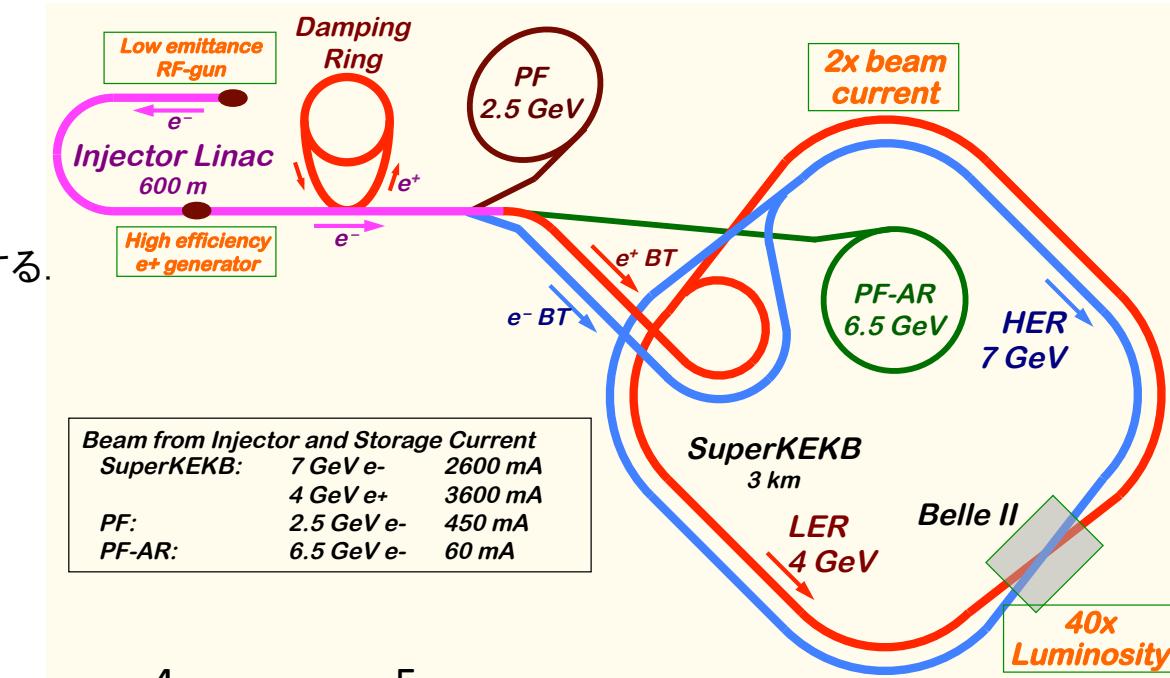
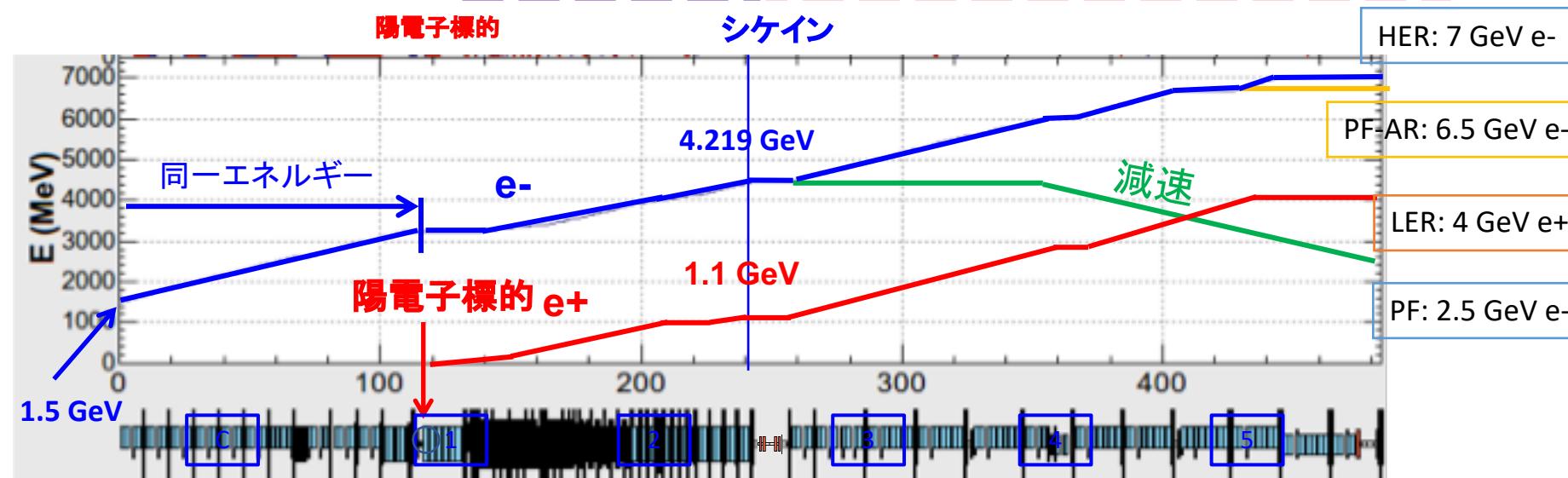
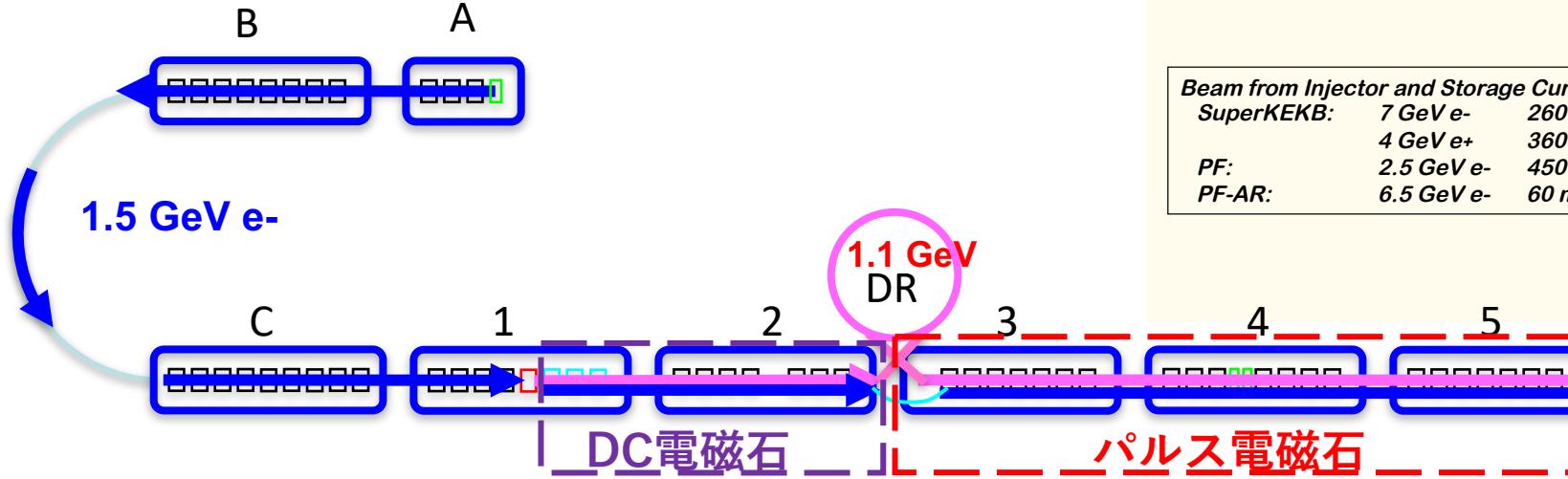


# Layout of LINAC, BT, Injection to MR

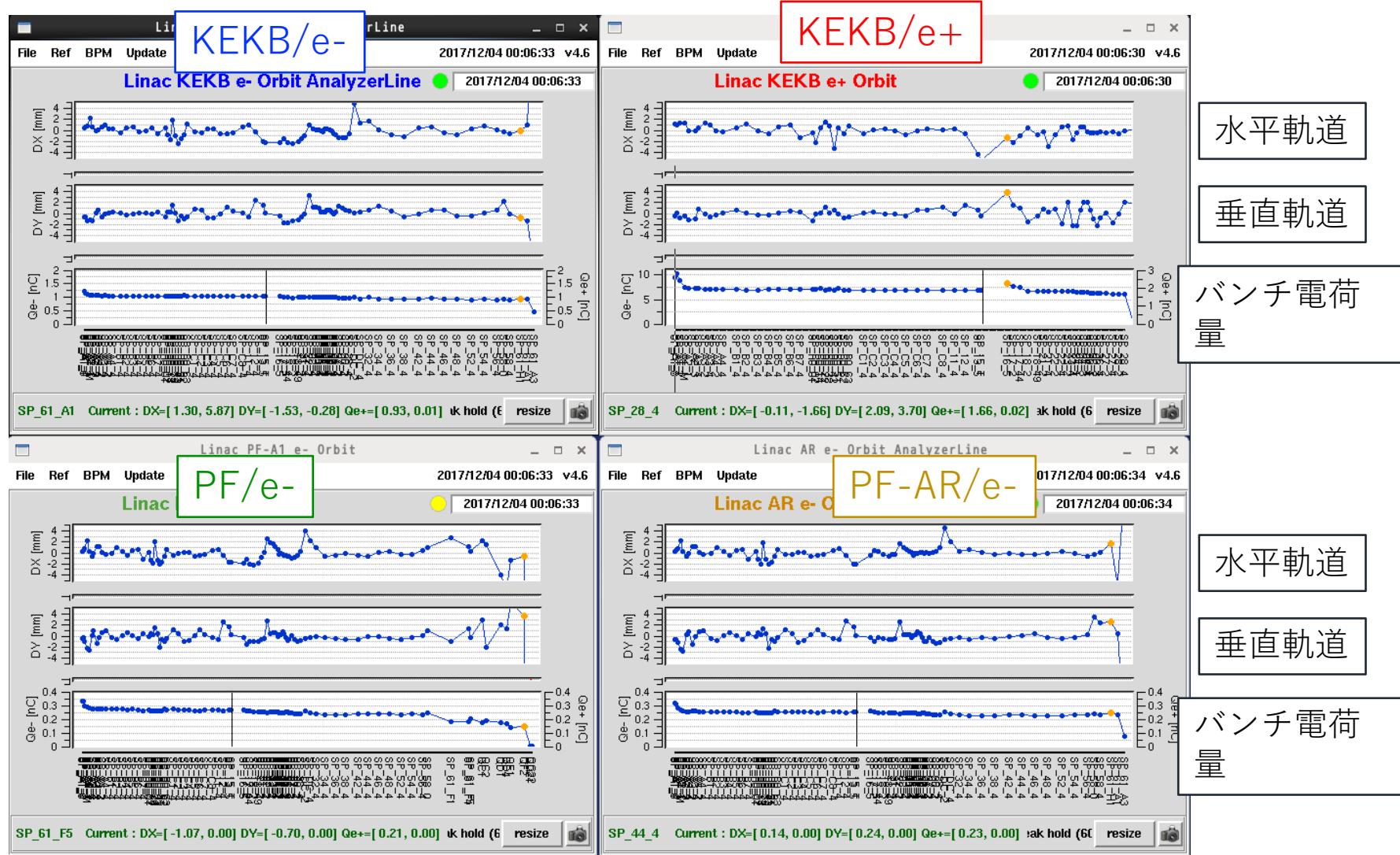


# 4 + 1 リング同時入射

- パルスごとに異なるバンチ電荷量、エネルギーのビームを加速、入射する。
- 50 Hz (20ミリ秒ごと)のパラメタ切り替えをおこなう。



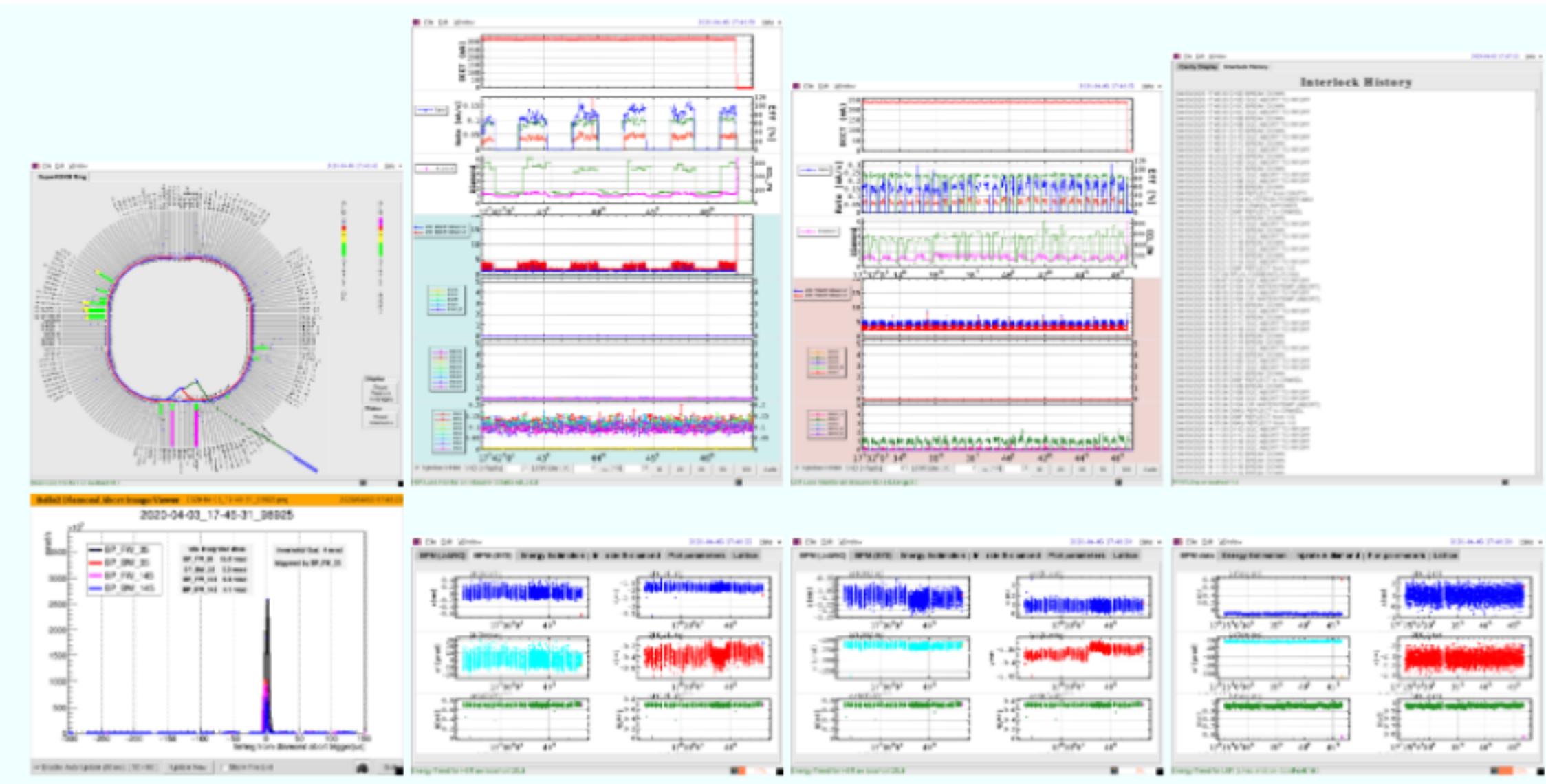
# 熱電子銃による同時ビーム運転(パルスごと切り替え) 4 リング同時入射



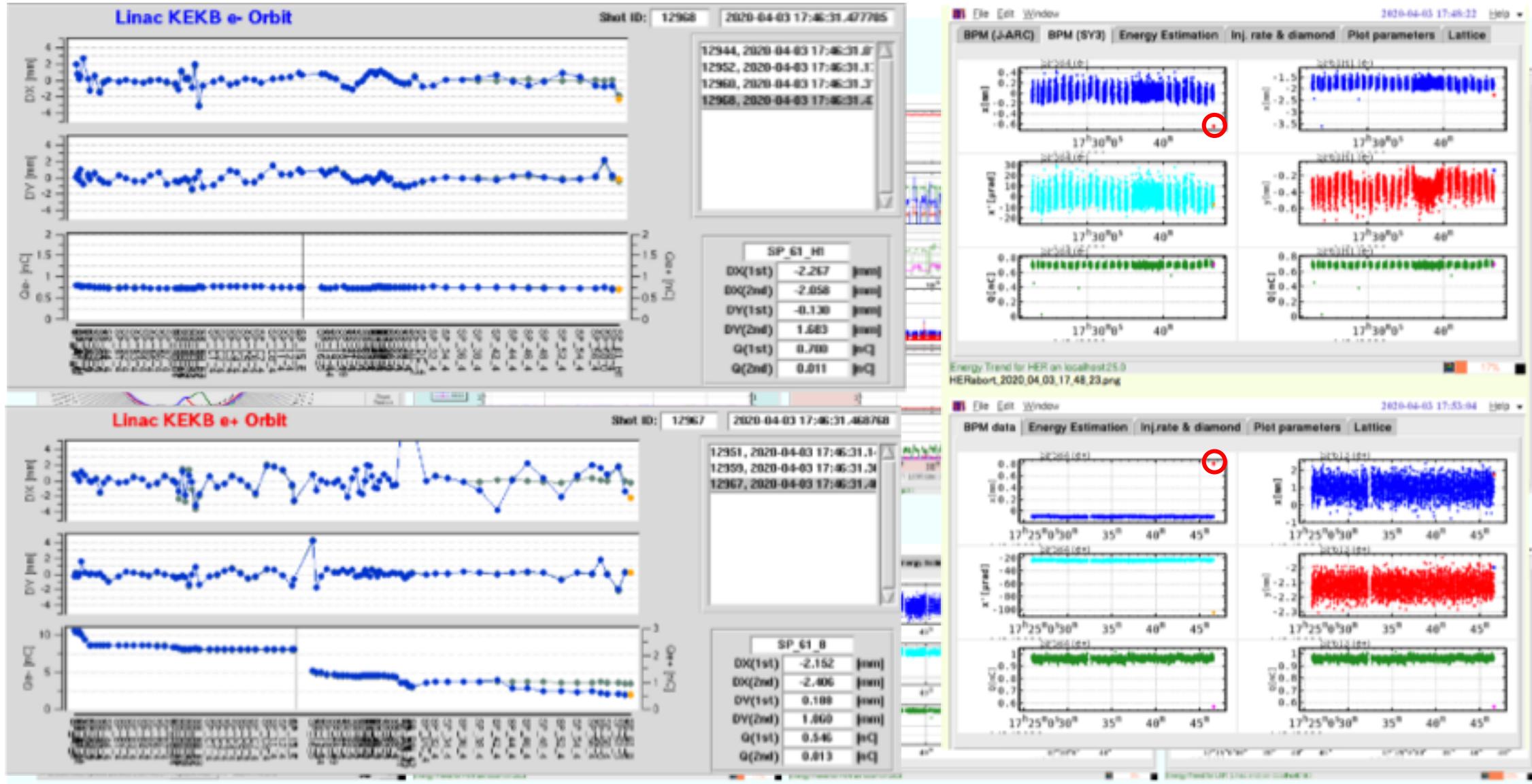
# 前回(2019.10.3)からの大きな変更点

- 問題点
  - LINAC Pulsed magnetのmis-triggerにより、Abortが多発している。
- e- beam
  - Cathode 交換
- e+ beam
  - BTでのEmittance増大がある程度抑制された

# LINAC Pulsed magnetのmis-triggerによるAbort、BGによる入射停止の多発

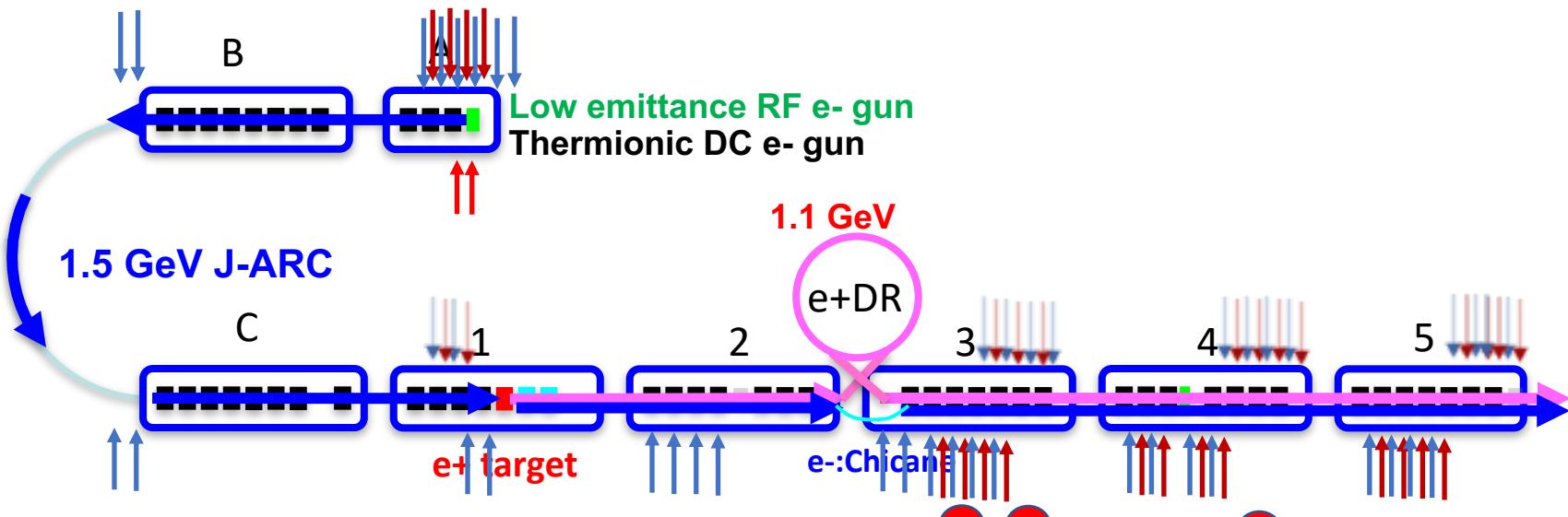


# LINAC Pulsed magnetのmis-triggerによるAbort、BGによる入射停止の多発

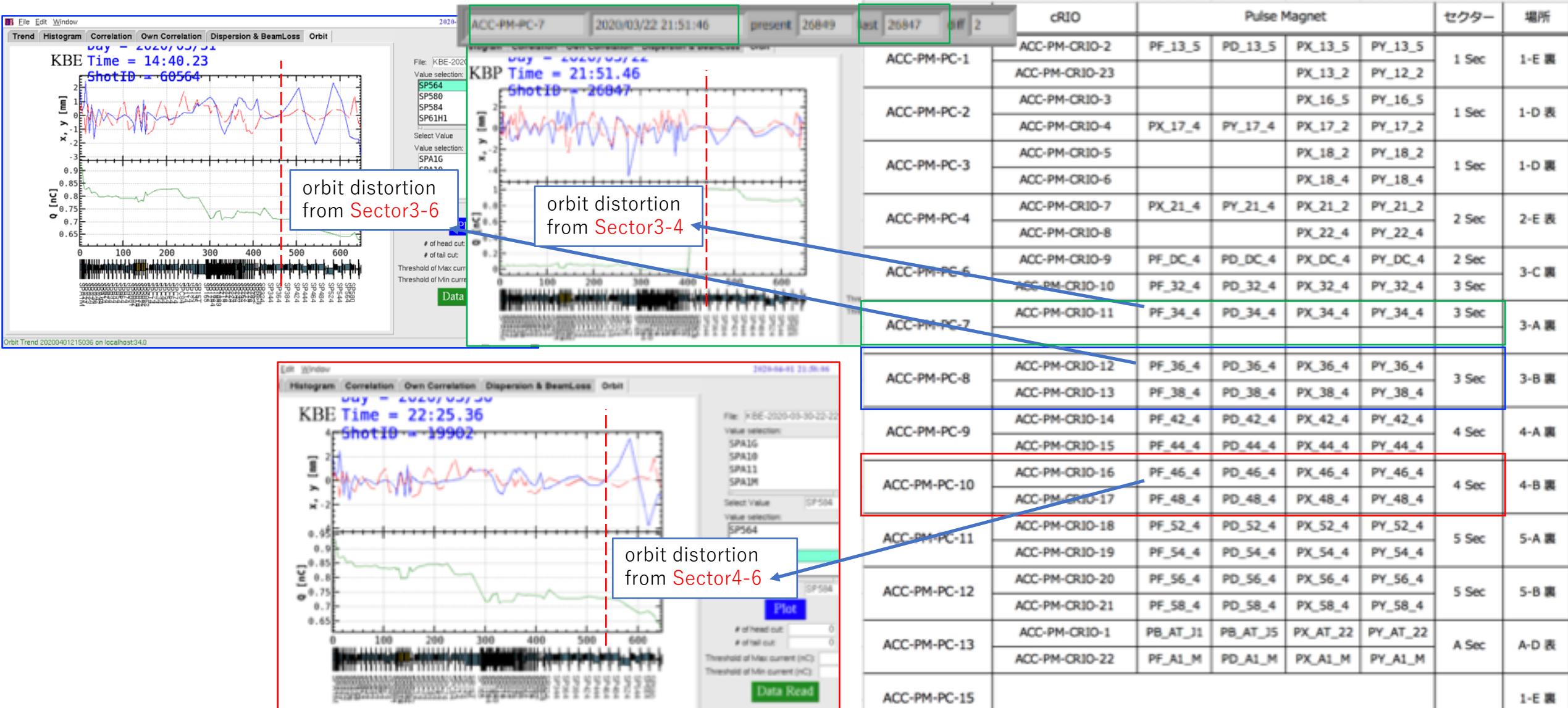


# Many pulsed magnets (Oct. 2017~) (Y. Enomoto et al.)

- Pulsed Quad x46, Pulsed Steering x80 , Pulsed bend x 2
- PXIe based controller x 16
  - Windows 8.1 Pro./LabVIEW/MRF EVR230



Most aborts triggered by misfire of some controllers.  
(ACC-PM-PC-7, ACC-PM-PC-8, ACC-PM-PC-10)



A mis-trigger was occurred at the time, called "Shot ID".

ACC-PM-PC-8	2020/03/31 14:40:23	present	60567	last	60563	diff	4
ACC-PM-PC-8	2020/03/31 14:40:23	present	60569	last	60567	diff	2

ACC-PM-PC-10	2020/03/30 22:25:36	present	19902	last	19899	diff	3
ACC-PM-PC-10	2020/03/30 22:25:37	present	19904	last	19902	diff	2

# Injection pattern Event system

example: 12.5Hz for both beam

**KEKB e- KEKB e+**

The screenshot shows two main windows. The top window is titled "InjPattern Multi -- newevg" and displays beam status for KEKB e- and KEKB e+. It includes sections for Beam (KBE, KBP, PFE, QFE, ARE, NIM), FP\_21\_T, KEKB Septum, and GR\_A1 LASER. A message "No Injection Mode" is displayed. The bottom window is also titled "InjPattern Multi -- newevg" and shows a grid of 50 rows and 25 columns for beam selection. An annotation "1unit: 20ms" points to the grid.

Index	1	2	3	4	5	6	7	8	9	10	11	12	13	14	15	16	17	18	19	20	21	22	23	24	25
Beam																									
FP_21_T																									
KEKB Septum																									
GR_A1 LASER																									

Index	26	27	28	29	30	31	32	33	34	35	36	37	38	39	40	41	42	43	44	45	46	47	48	49	50
Beam																									
FP_21_T																									
KEKB Septum																									
GR_A1 LASER																									

1unit: 20ms

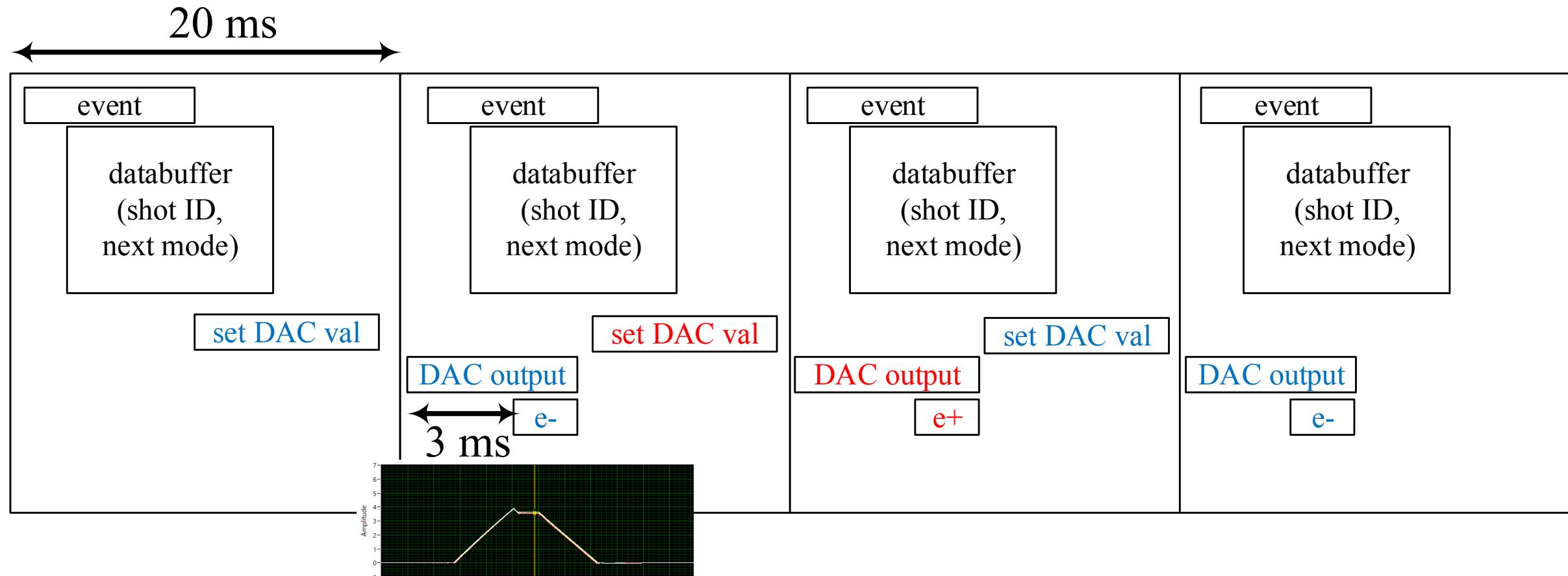
The screenshot shows the "Pattern" tab of the InjPattern Multi -- newevg software. It includes sections for Priority (KEKB e+, KEKB e-, PF-A1 e-, AR e-, KEKB e- Study, KEKB e+ Study, PF-A1 e- Study, PF-3T e- Study, AR e- Study, PF-3T e-), Beam (KBP Beam Gate, KEKB e- (KBE), KEKB e+ (KBP), PF-3T e- (PFE), PF-A1 e- (QFE), AR e- (ARE)), and other controls (Up/Down, JBP Req Rep [Hz], GR\_A1 Rep Limit [Hz], DR Stored Time, KBP, Bucket Selection). A message at the top right indicates "set pattern finish" for various dates and times.

...

# Operation sequence of pulsed magnet

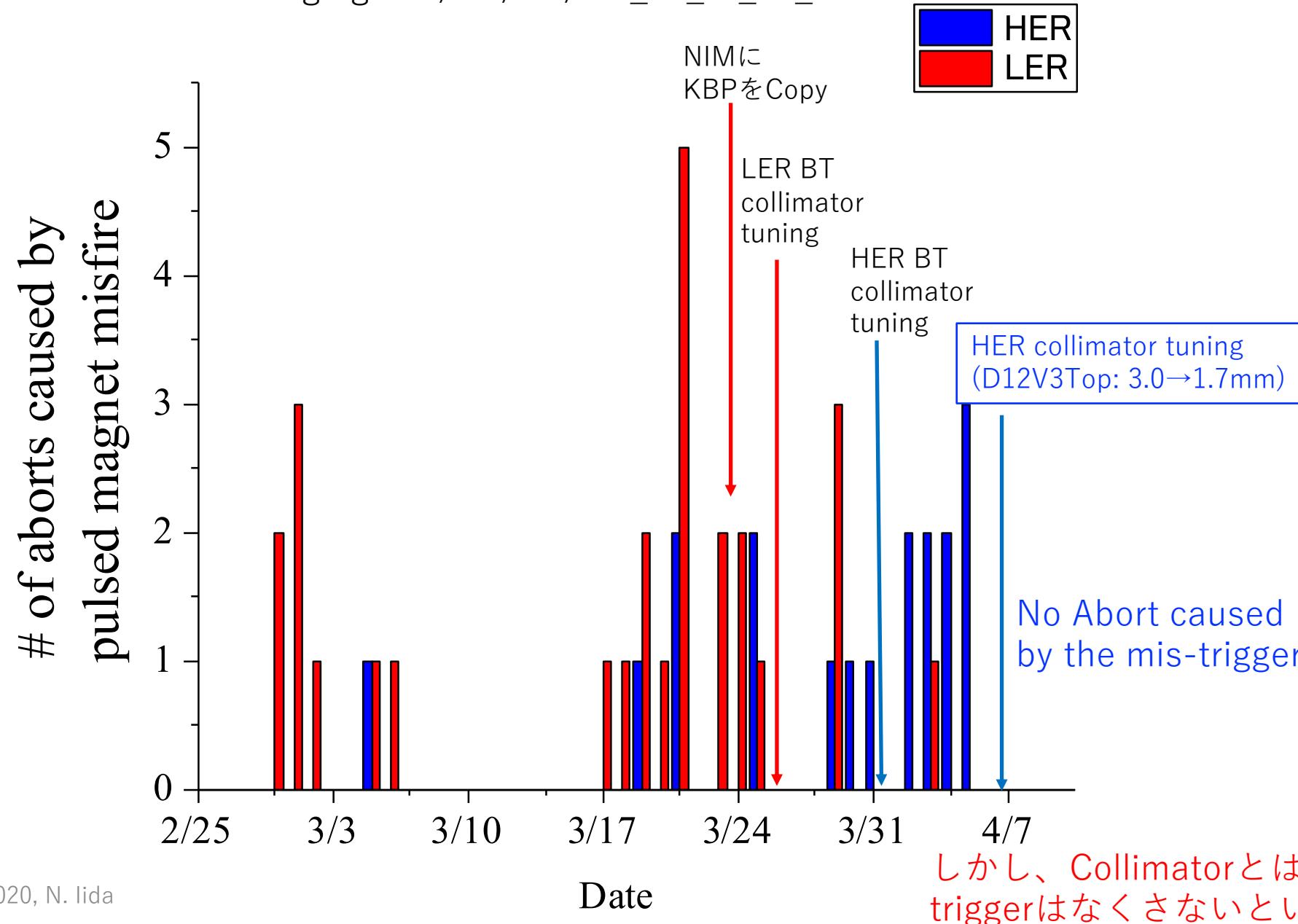
M. Satoh

- In some events, (what's happening is not clear)
  - DAC value setting is delayed or failed. DAC is not trigger waiting mode.
  - Trigger is delayed or missing.
- It could cause bad beam orbit and eventually MR beam abort.

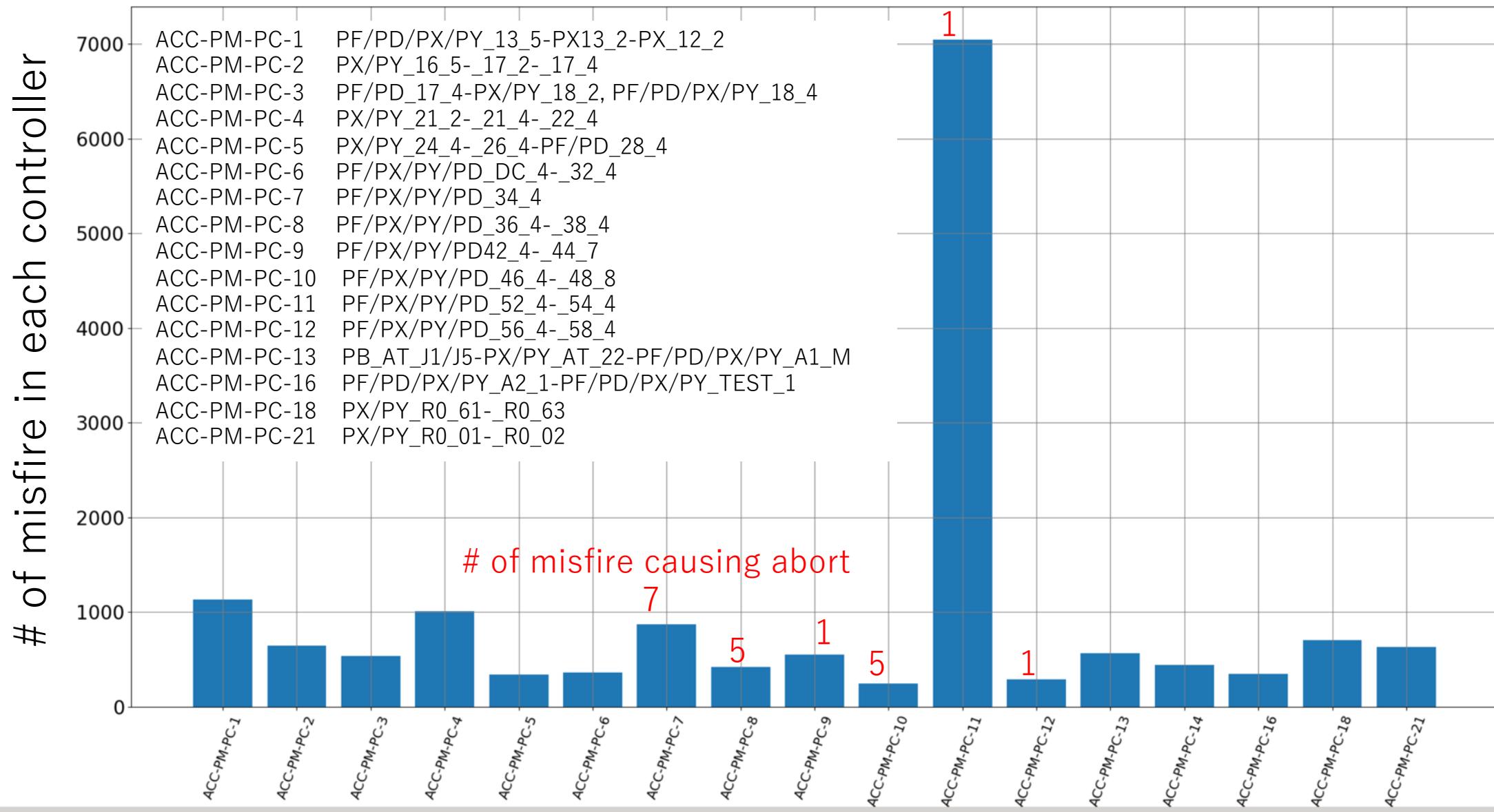


Most cases were caused by misfire of ACC-PM-PC-8 controller  
managing “PF/PX/PY/PD\_36\_4-\_38\_4”.

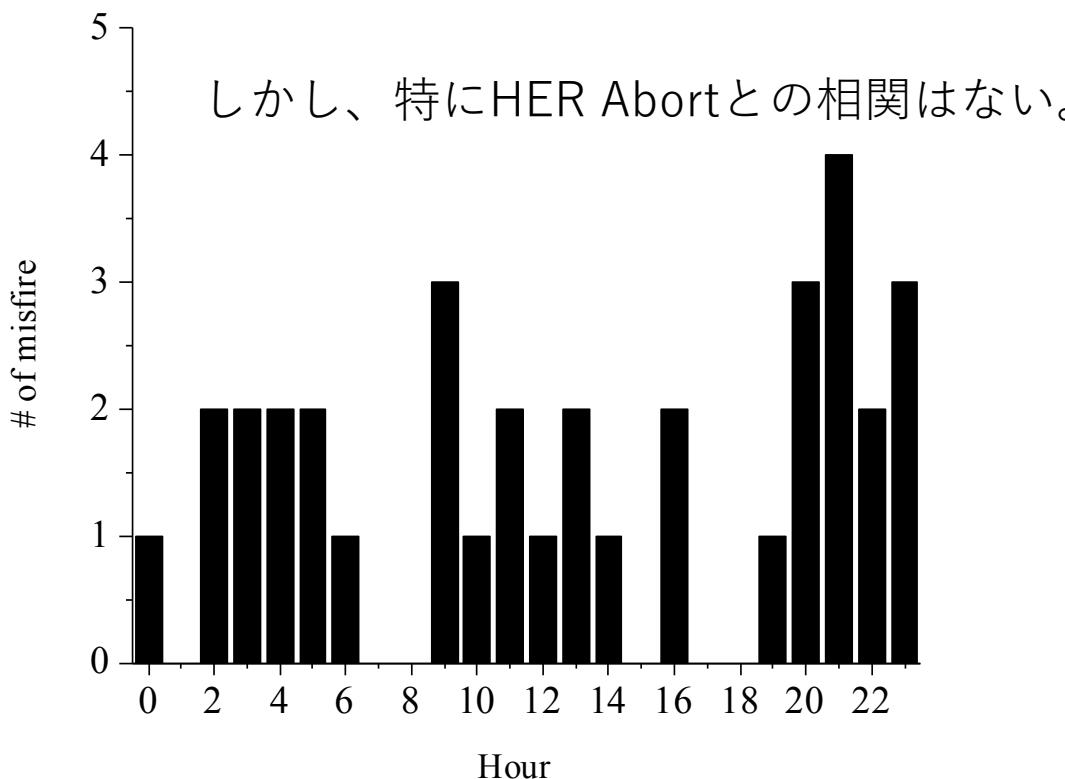
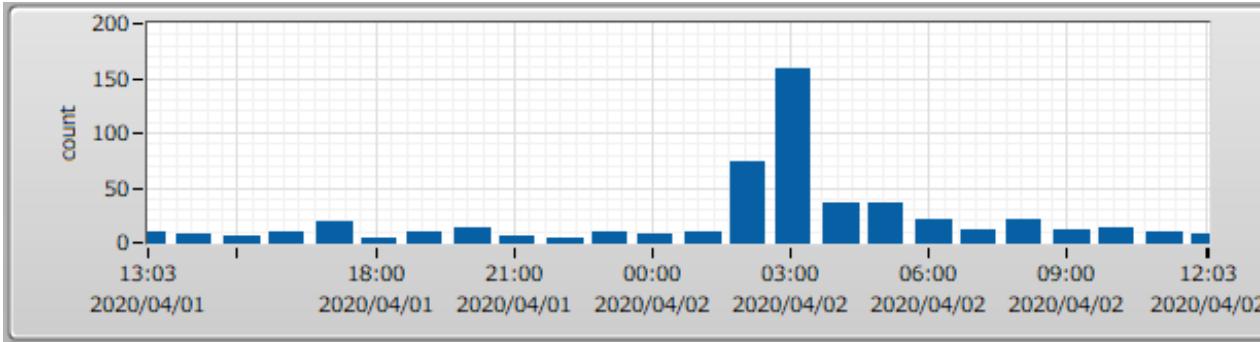
M. Satoh  
2020.4.8 10:00現在



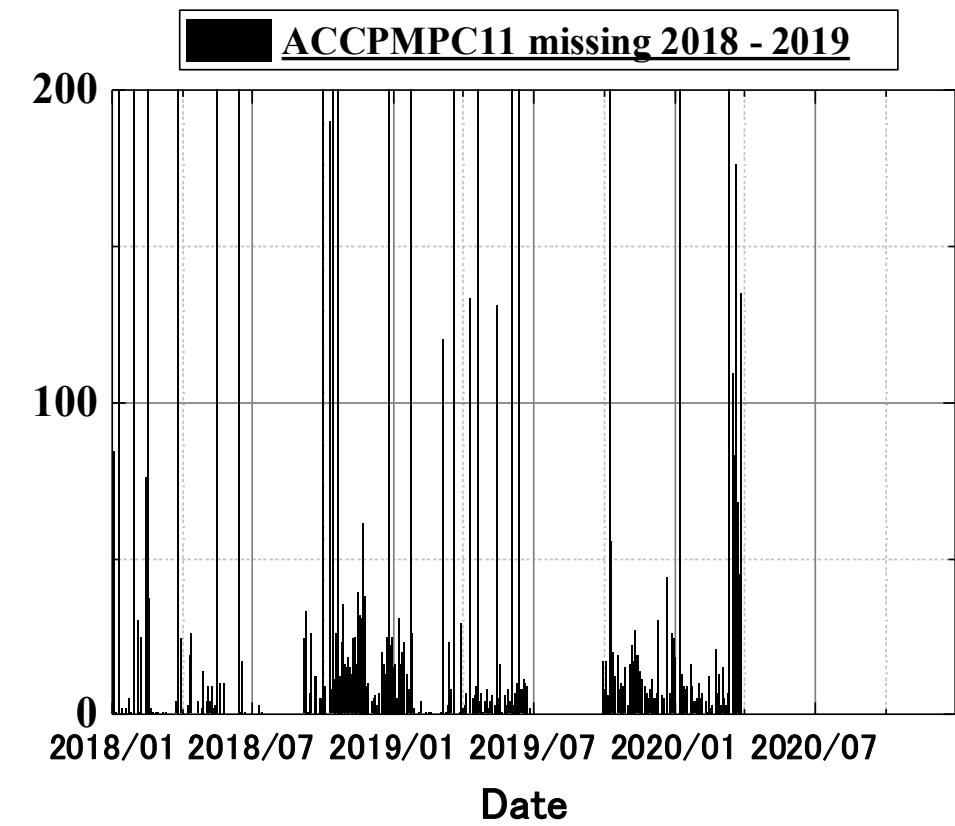
# Pulsed magnet misfire events: 2/29 – 3/31 (17/day/controller in average)



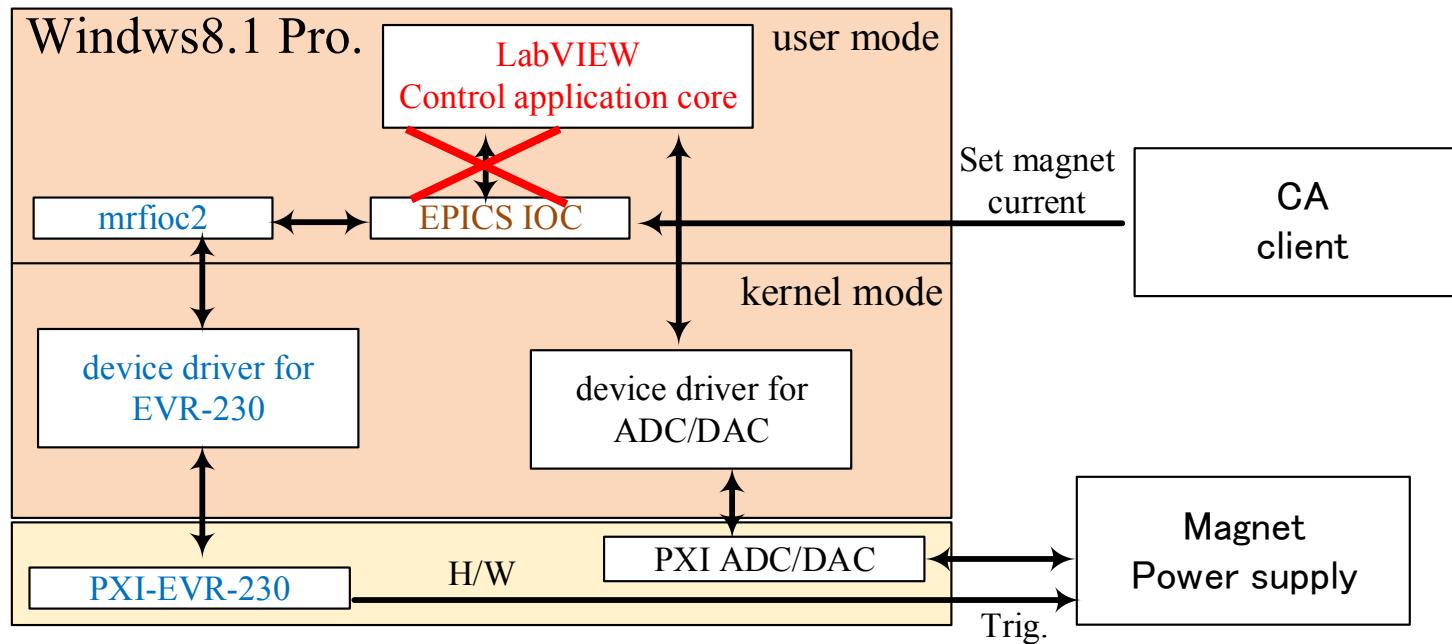
3:00頃にmis-triggerが多発している



2018年には、mis-triggerはほとんどなかった。

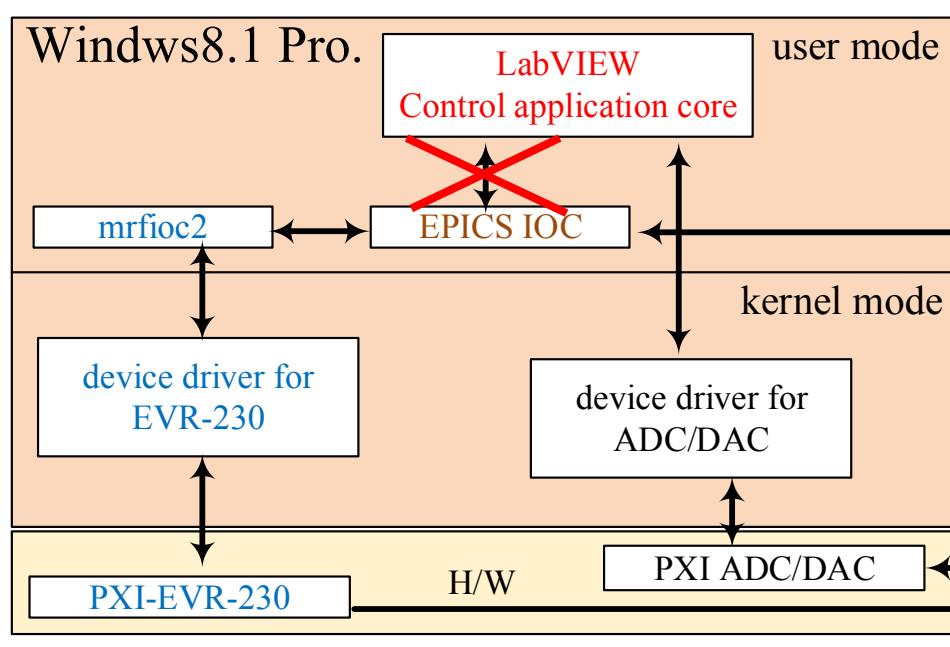


# Current software structure



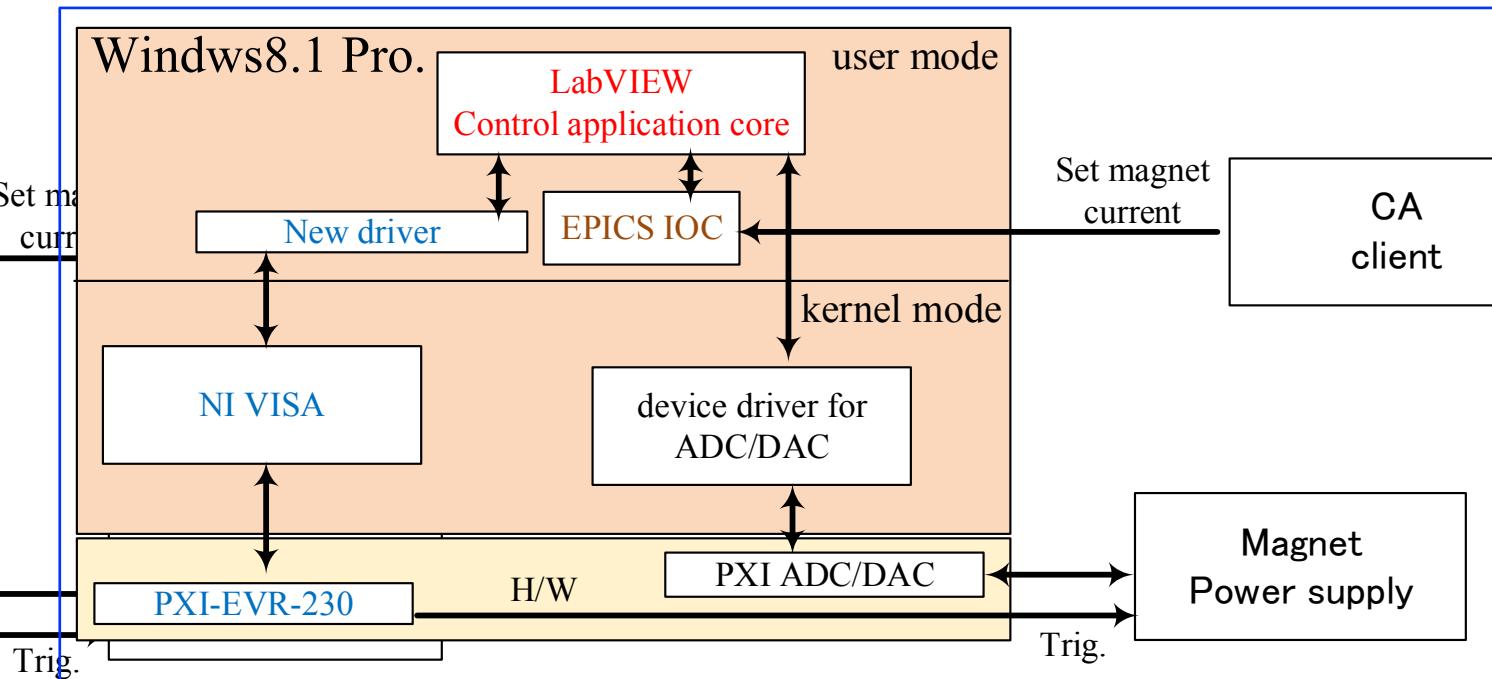
In some events, LabVIEW/EPICS IOC communication is delayed or failed.

# Current software structure



In some events, LabVIEW/EPICS IOC communication is delayed or failed.

# New software structure under development

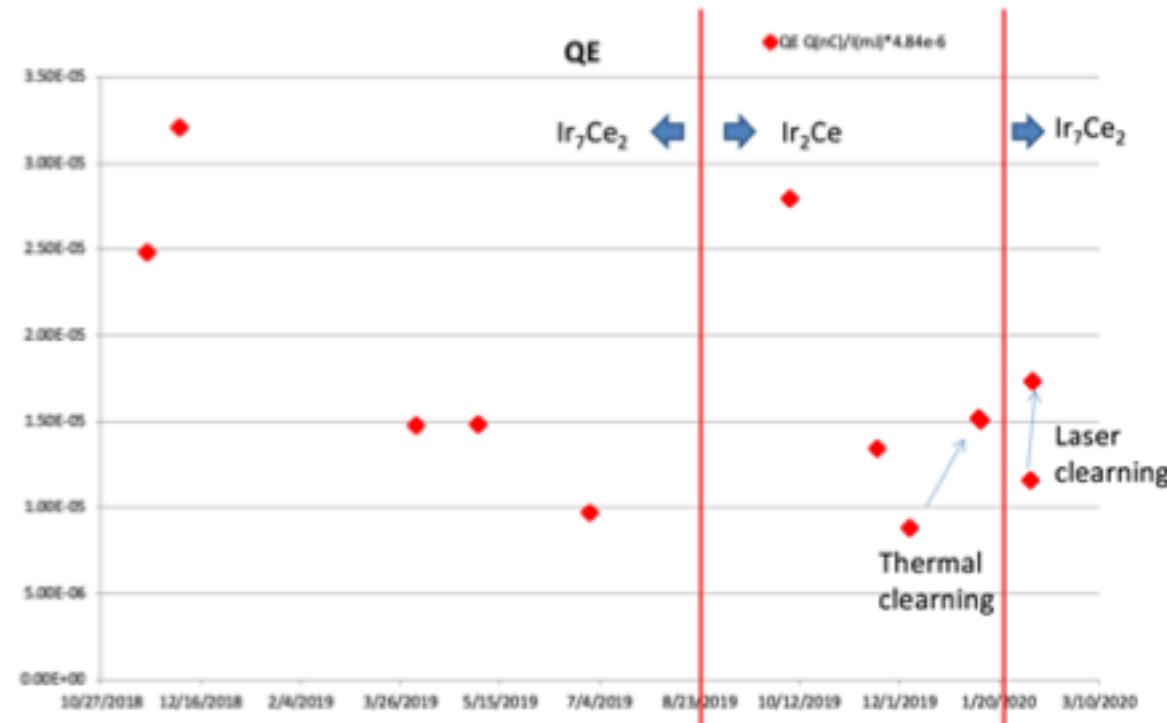


NI VISA based EVR driver (under development)  
is currently promising candidate.  
(w/o EPICS IOC for EVR control)

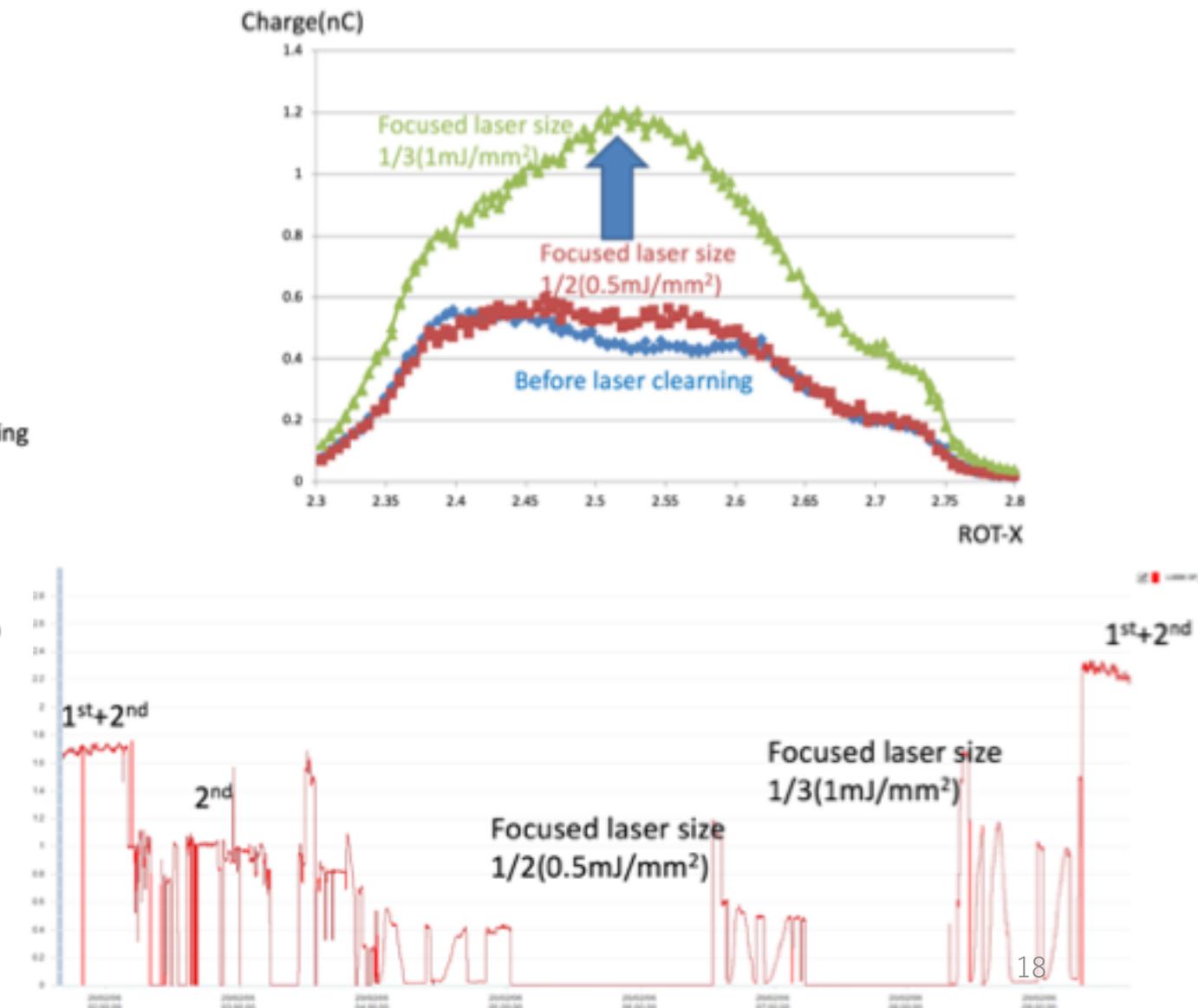
4/9(木)メンテ日、置き換え作業予定。  
万が一ダメだった場合でも2時間で戻せる。

# Electron beam (RF gun )

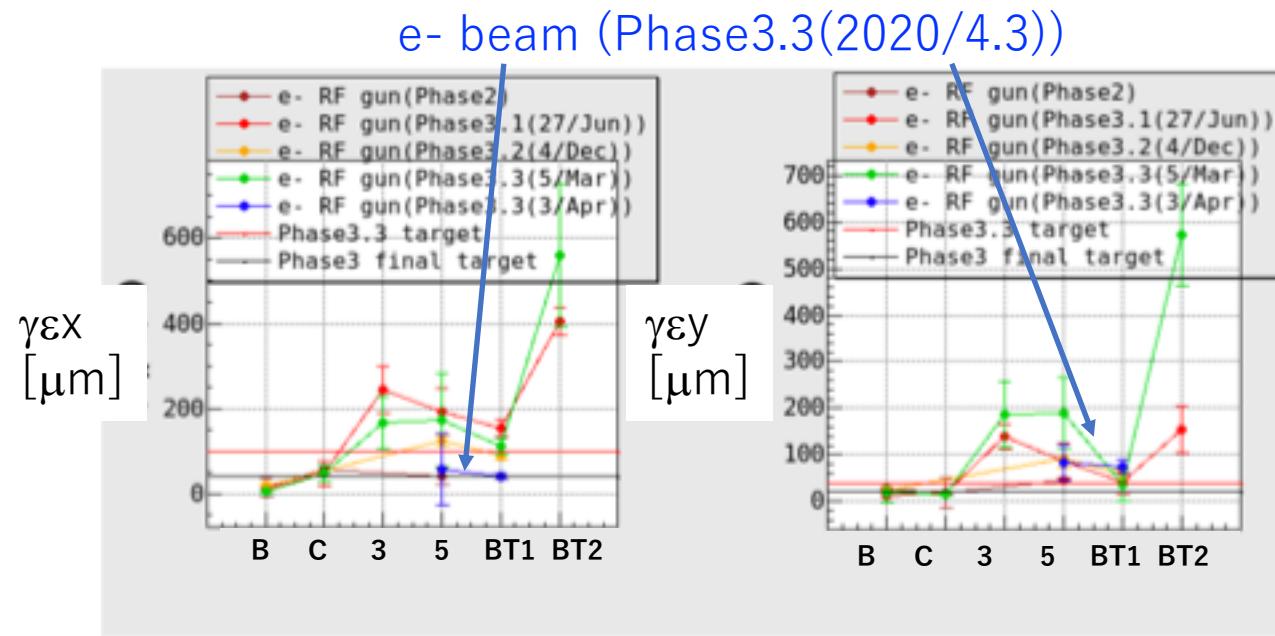
# RF gun Cathodeの交換前後の量子子効率



# Laser cleaningの効果



# Measured Emittance



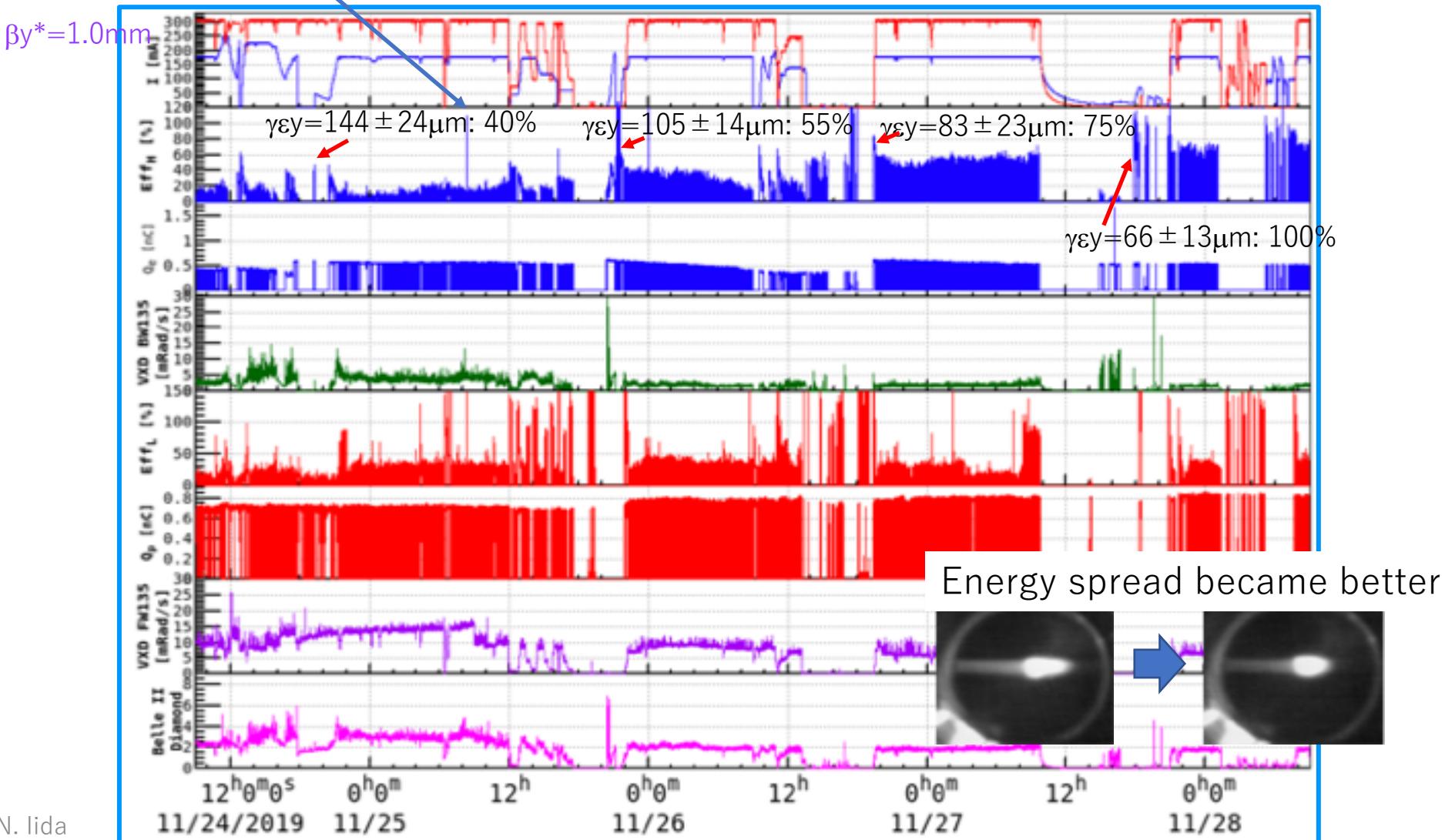
Phase3.3	e+	e-
$\gamma\epsilon_x$ [ $\mu\text{m}$ ]	150	100
$\gamma\epsilon_y$ [ $\mu\text{m}$ ]	30	40
$\sigma_\delta$ [%]	0.16( $1\sigma$ )	0.1( $1\sigma$ )

# 1. Injection efficiency and background

The injection efficiency increased as emittance decreased by tuning day

Phase3.2  
2019c(Autumn)

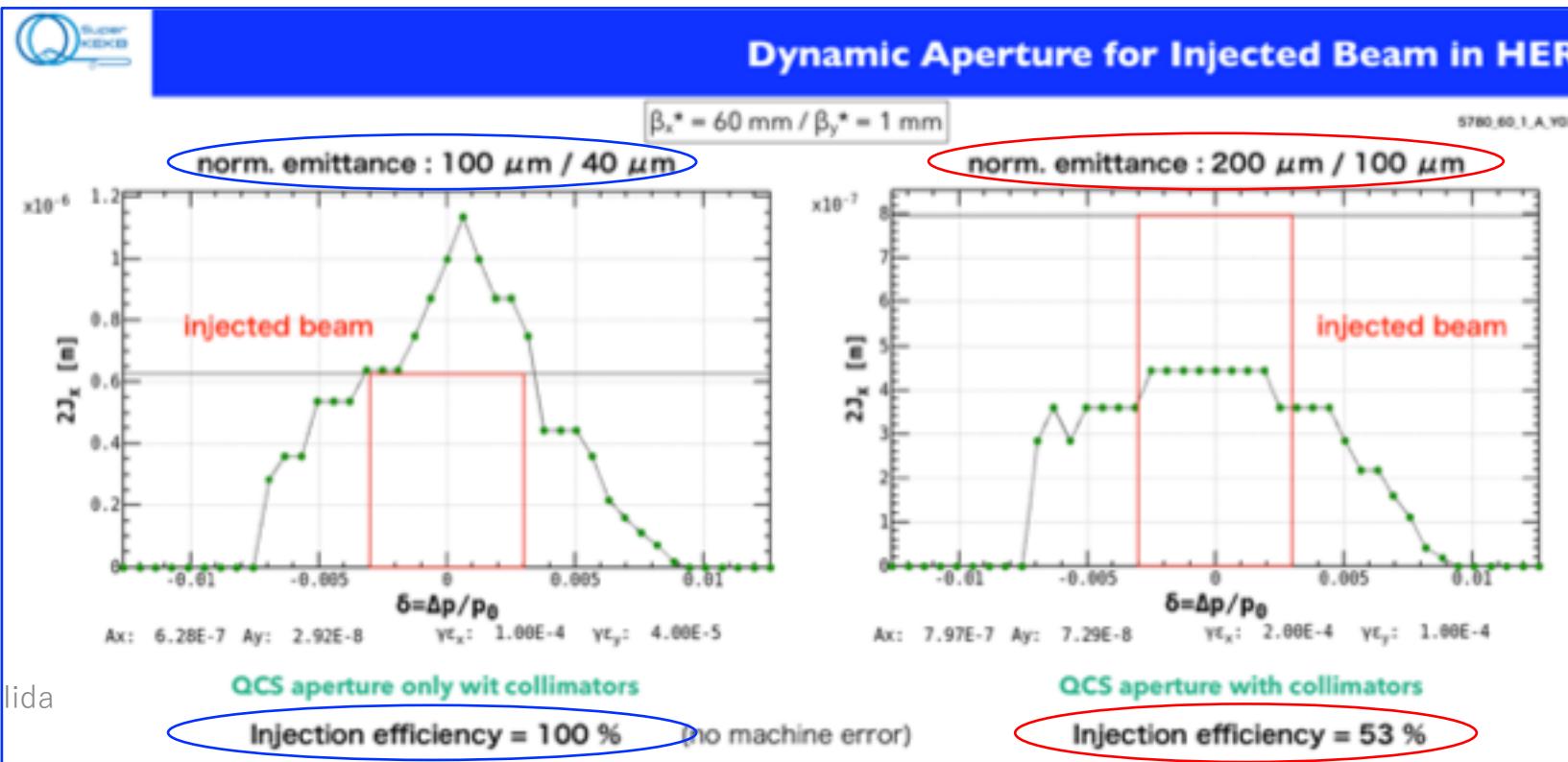
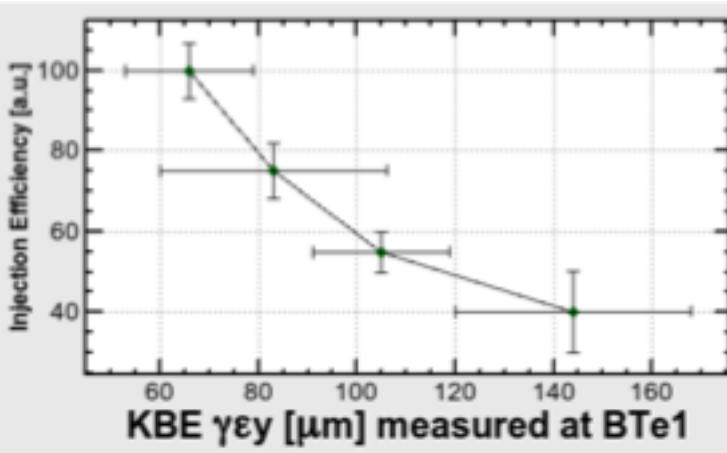
These efficiencies are calculated at the low current beam in the HER.  
→ The effect of Touschek lifetime can be neglected.



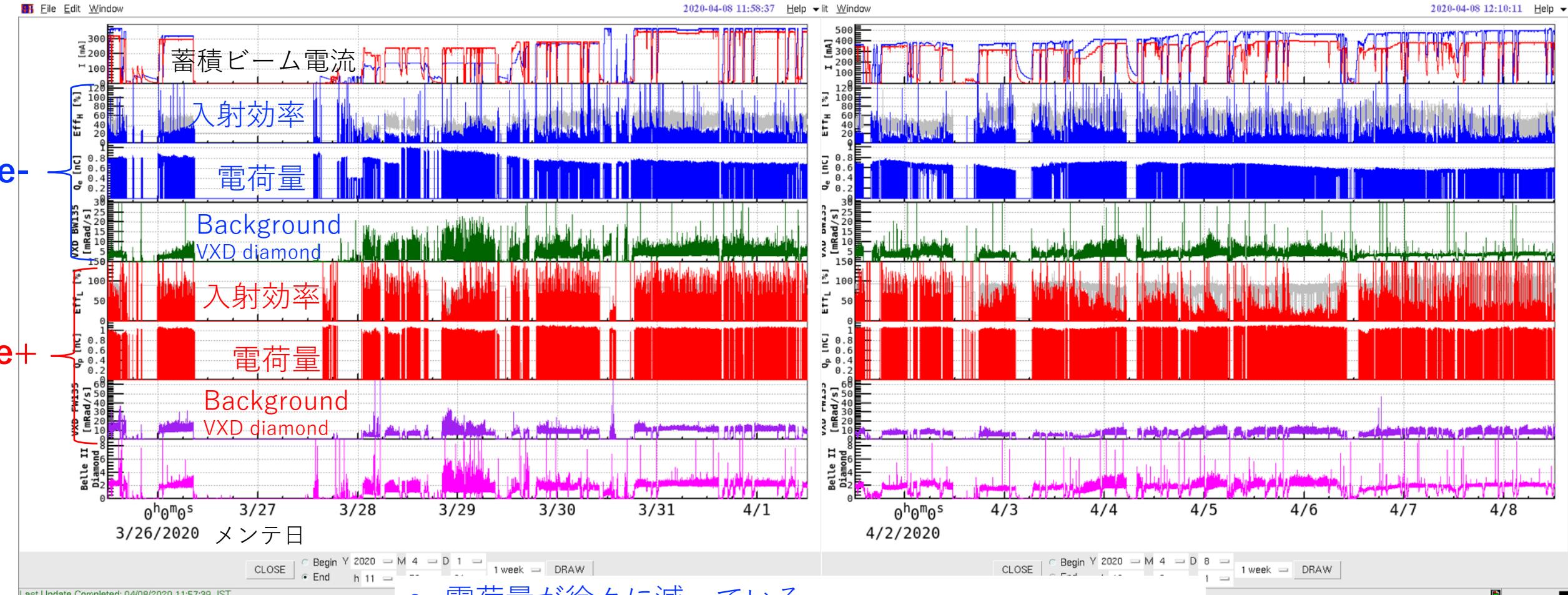
# 1. Injection efficiency and background

## Vertical emittance vs. HER Injection efficiency

How keep?  
How to stablize laser



# 入射まとめ（二週間）

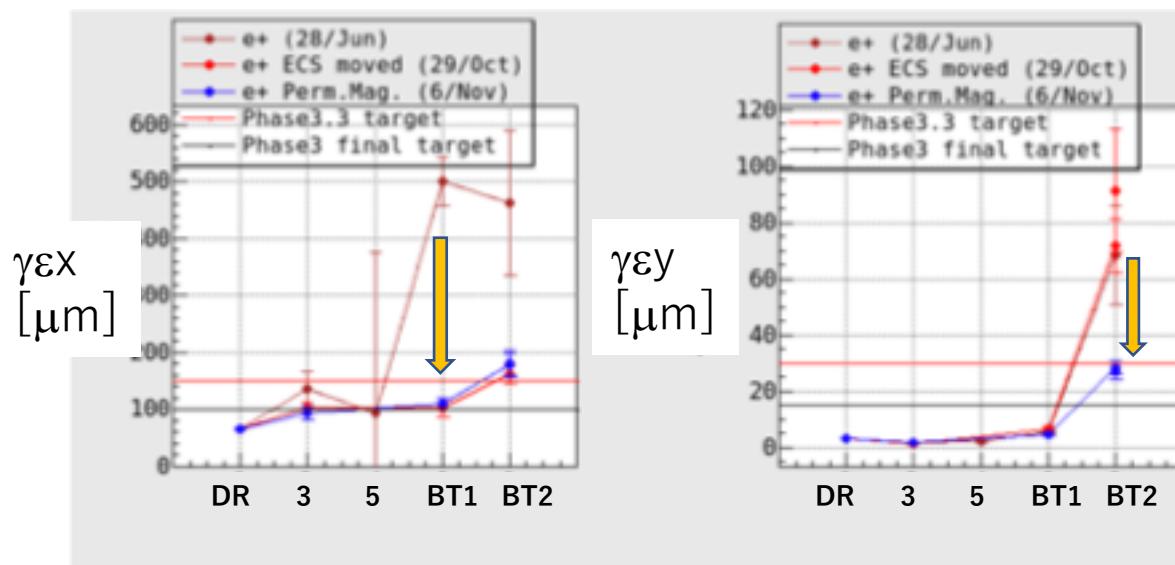


e- 電荷量が徐々に減っている。  
蓄積ビーム電流が高くなるにつれて、入射効率が下がる。  
今のBackgroundは比較的良好。

# Positron beam

# Measured Emittance

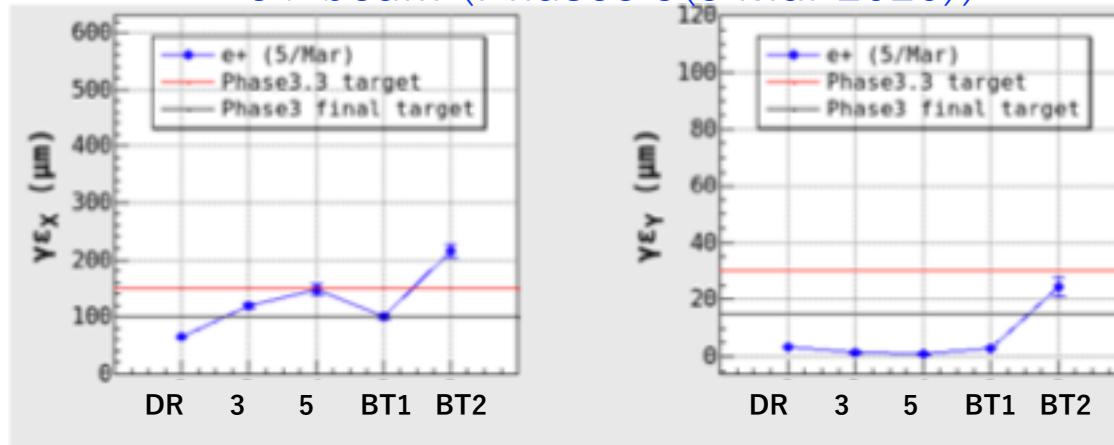
e+ beam (Phase3.2(6.Dec.2019))



SuperKEKBからの要求値

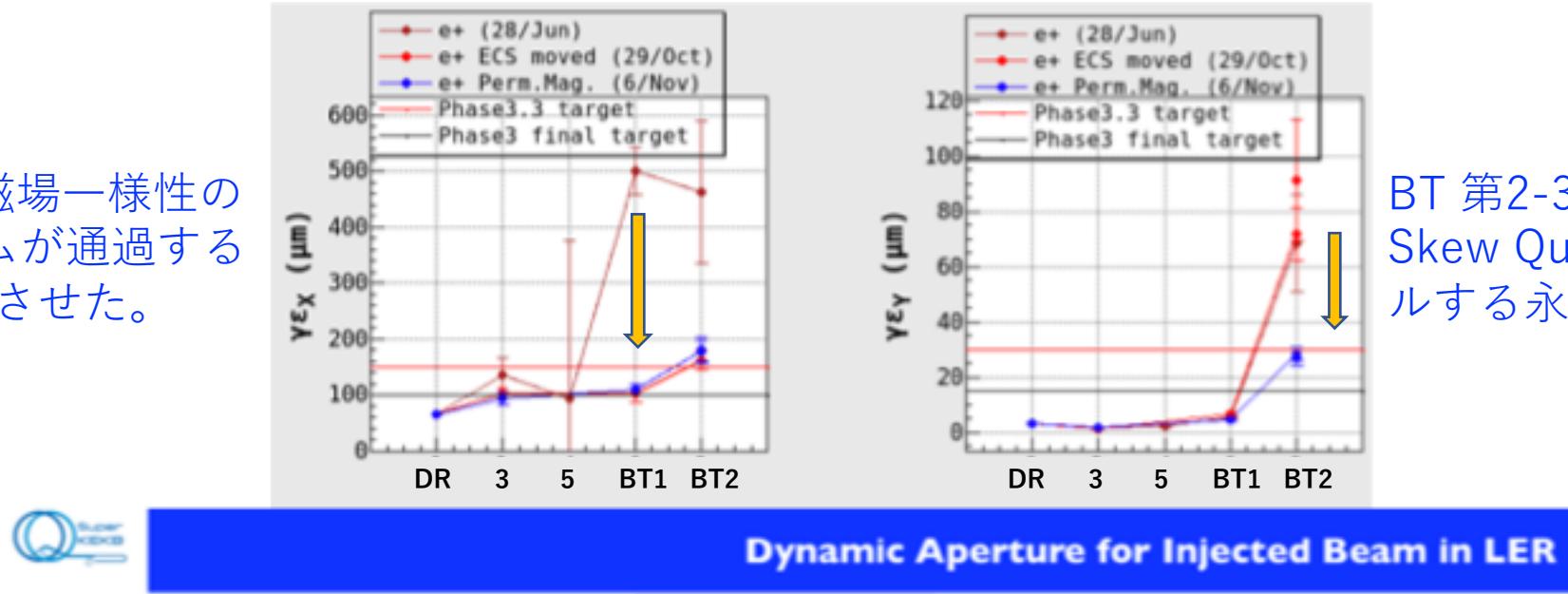
Phase3.3	e+	e-
$\gamma\epsilon_x$ [μm]	150	100
$\gamma\epsilon_y$ [μm]	30	40
$\sigma_\delta$ [%]	0.16(1σ)	0.1(1σ)

e+ beam (Phase3.3(5.Mar.2020))

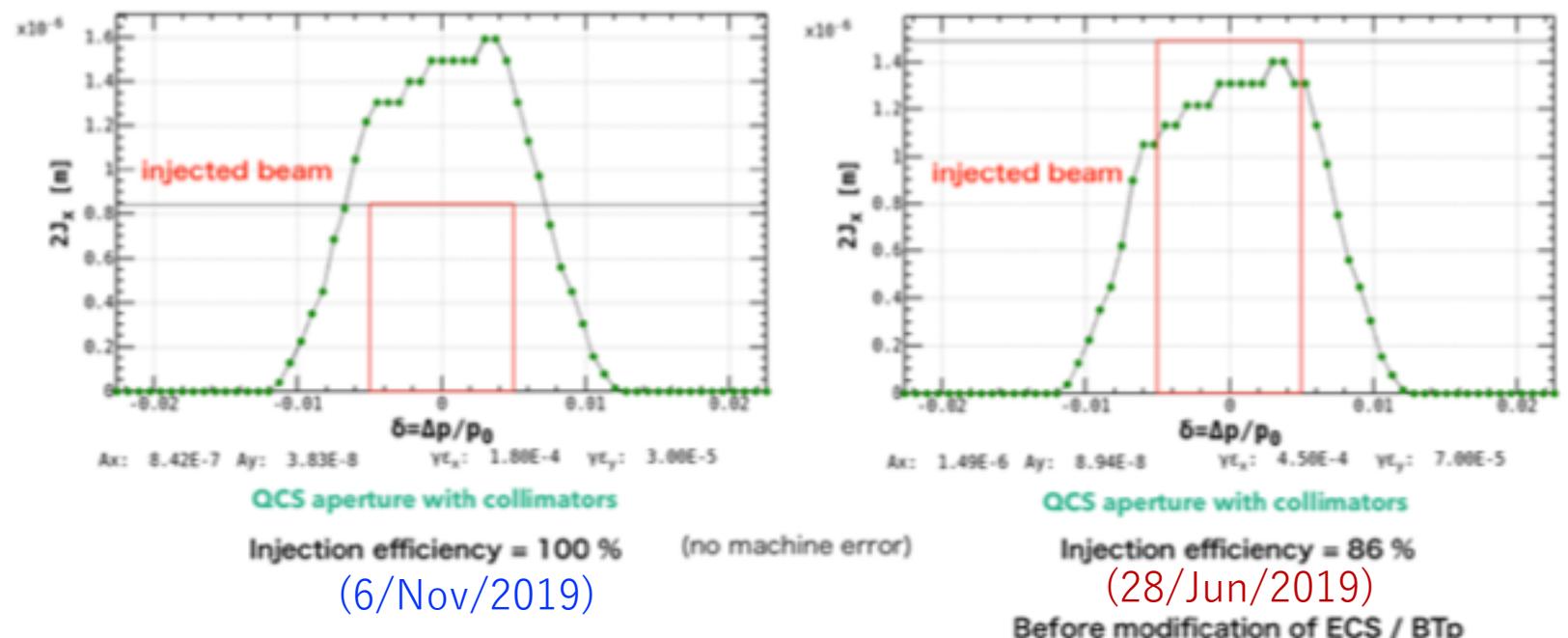


# LER入射

ECS/SY3 Bendの磁場一様性の良い場所を、ビームが通過するようにBendを移動させた。  
(約10mm)



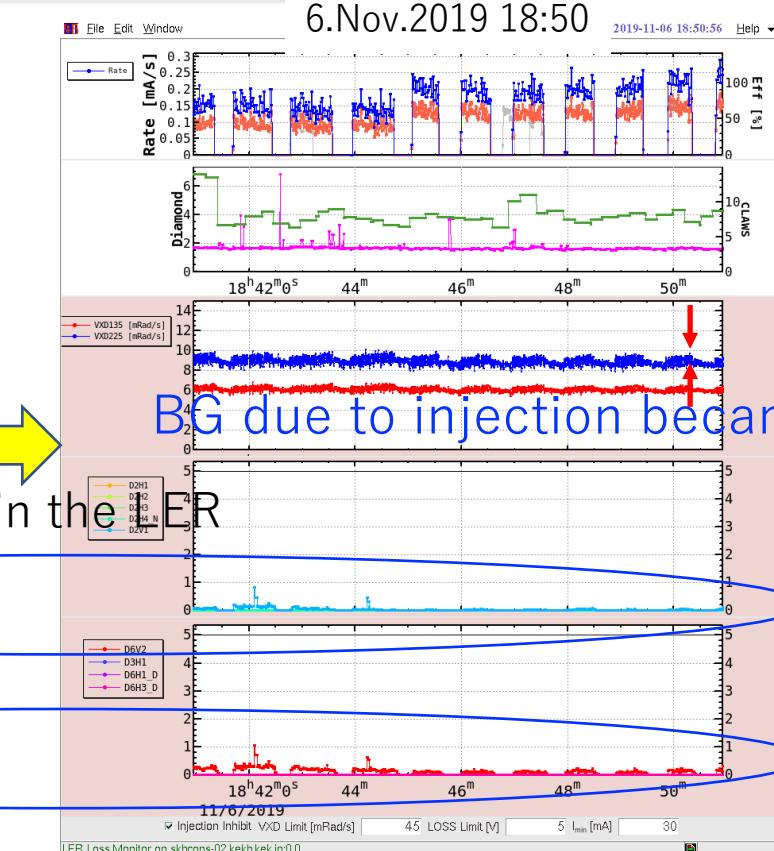
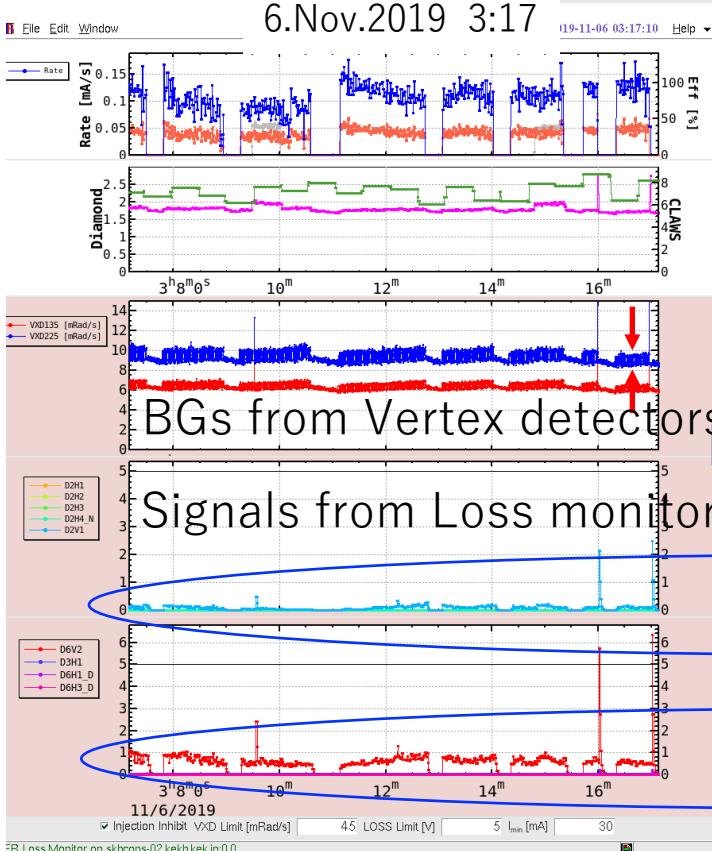
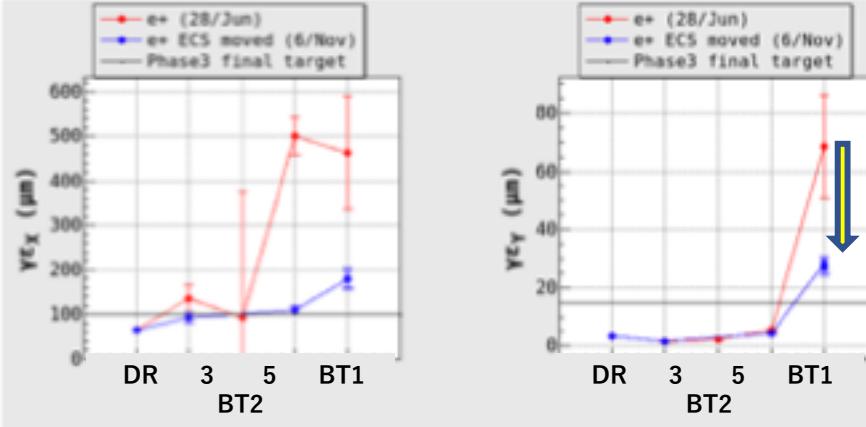
Y. Ohnishi



# 1. Injection efficiency and background

- **LER**

When the vertical emittance was improved,



# その他も含めたまとめ

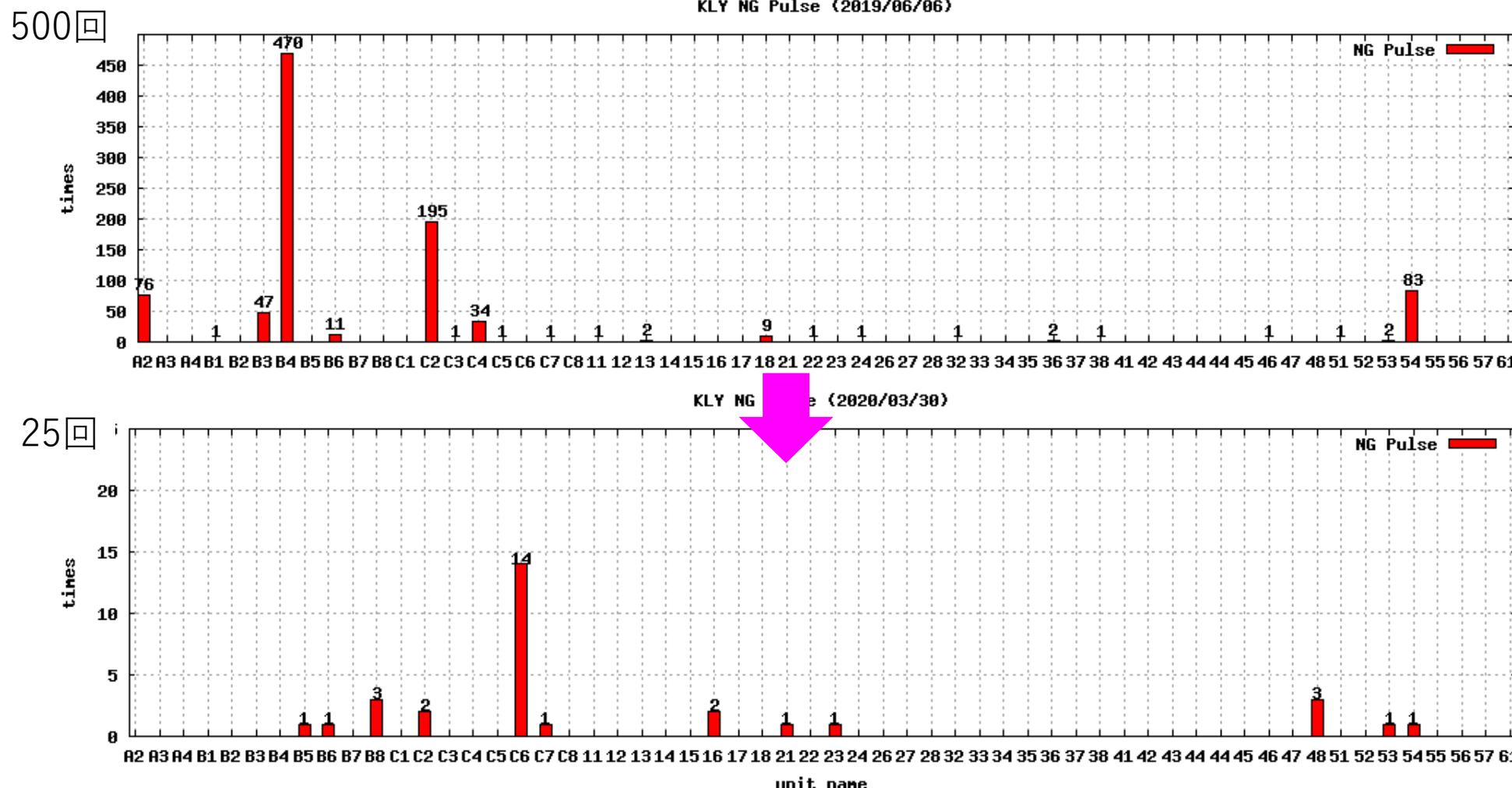
- 改良点
  - e+入射ビームのエミッタンス改善 (SY3/ECS Bend移動、永久磁石のSkew quadを、BTアーク部にInstallation)
  - e- 量子効率の電荷量依存性 (レーザークリーニングが有効)
  - 2バンチ入射最適化 (ECS、BCSの加速管HV Timing調整)
  - RF位相変動の緩和
    - Es下げた
    - DeQing trigger unit
  - Operationで、生の入射効率表示
- 問題点
  - パルスマグネットのmis-triggerによるAbort
  - さらなるEmittance増大の解消

# Pulse shortening

頻度の高い箇所の高圧を下げる。

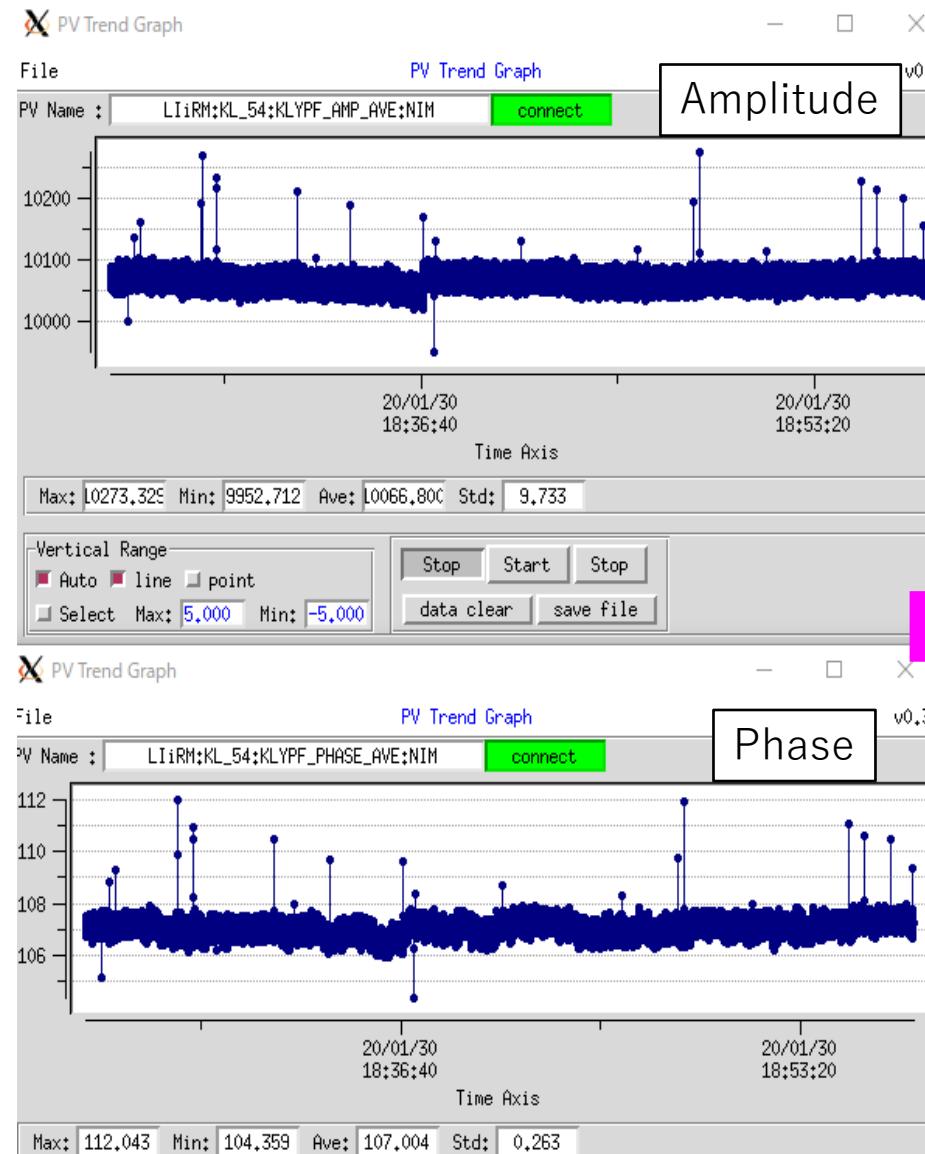
## 1 Day Summary

- KL\_A2 Es: 42→40kV @2020,Jan
- KL\_B3 Es: 42→40kV
- KL\_B4 Es: 42→38kV
- KL\_C2 Es: 42→40kV
- KL\_C4 Es: 42→40kV
- KL\_54 Es: 42kV → 38 kV



# Improvement of DeQing Trigger Unit

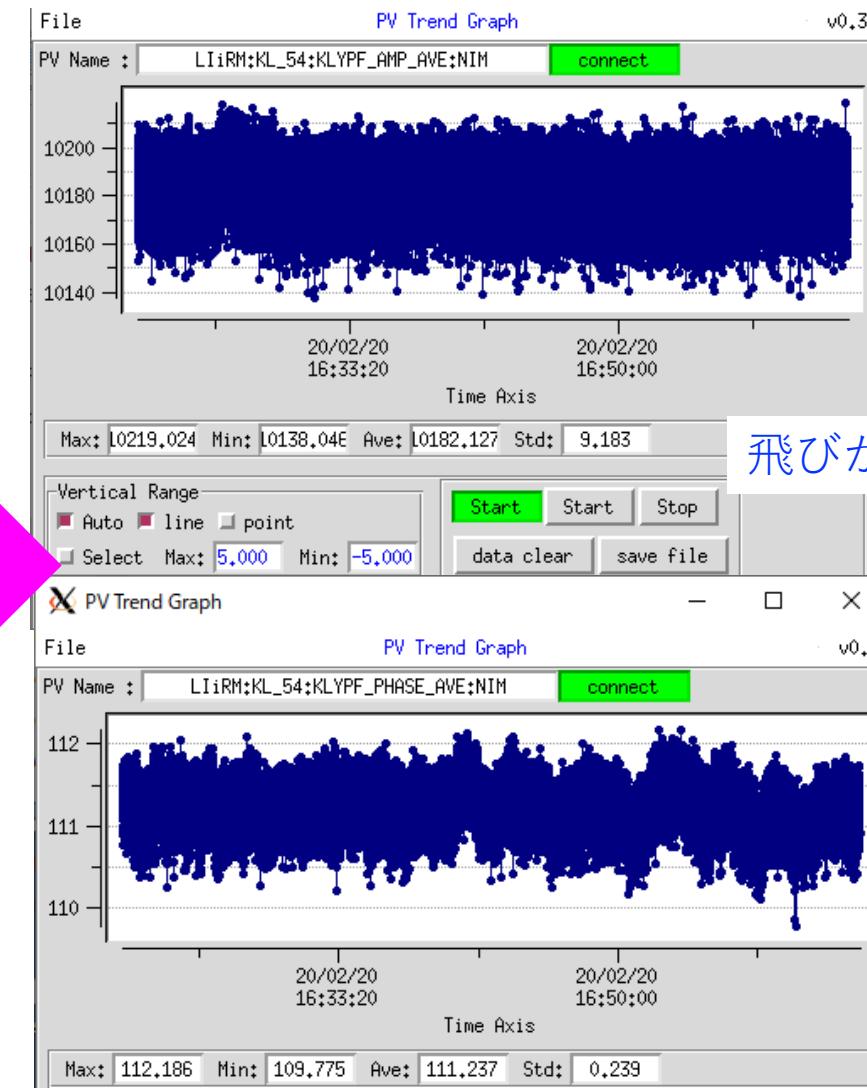
共振充電電源の箇所で振幅・位相にトビが見られた



Esの設定値をアナログレベル信号で受信しているが、受信タイミングをノイズの影響がないところに同期させることで改善

T. Miura

21ヶ所対応@3/12  
A2,A3,B5,B6,B7,35,41,42,43,45,46,  
47,48,51,52,53,54,55,56,57,61



# LINAC、BT改造

- 2020年夏の作業

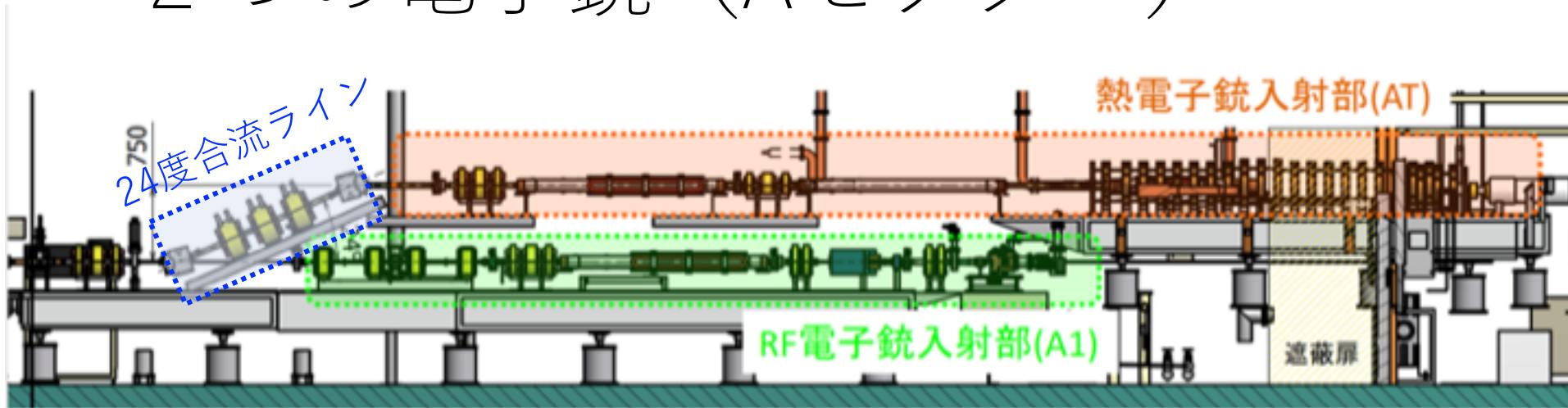
- 熱電子銃とRF電子銃のMerger lineのPulsed bendの50Hz化
- 加速管 4本(4\_4)/12本(3年計画)/230本
- FC入れ替え (放電しにくくなる)
- Positron capture section改造 (BPM, Steeringのインストール)
- Collimator増設 (Energy cut用 : SY3/ECS Chicane、e-BT)
- BT BPM (一部) を、リベラへの置き換えによるLINACとの同期、高速化
- BT Screen monitor (一部) 高性能化

- 長期的な改造

- パルスマグネット増設
- 2バンチ目だけキックする高速Pulsed steering

# Backup slides

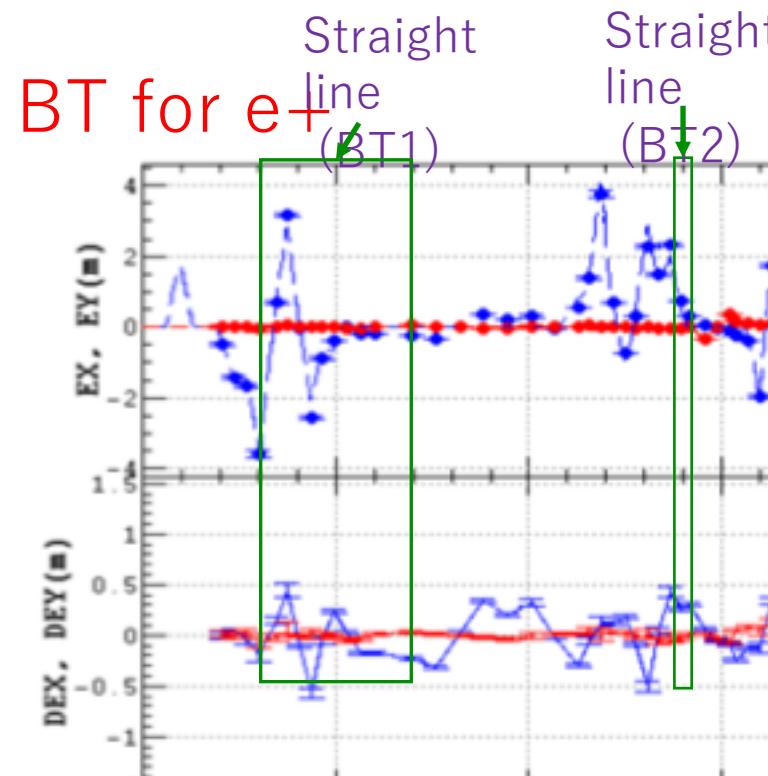
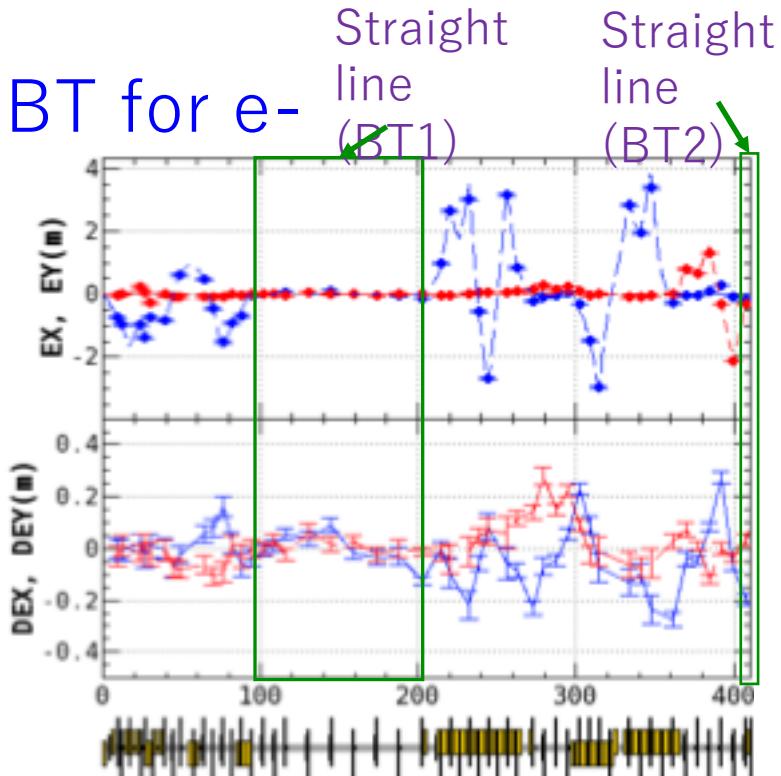
# 2つの電子銃 (Aセクター)



- 热電子銃
  - LER, PF, PF-AR (, HER)
  - 热電子銃
  - SHB1(114MHz)
  - SHB2(571MHz)
  - Pre-buncher
  - Buncher
  - 加速管(2mx2本)
- RF電子銃
  - HER
  - 0-deg QTW RF gun
  - 90-deg CDS RF gun
  - Bunch Compress System(BCS)
  - 加速管(2mx1本)
- 24度合流ライン
  - BendのChamber発熱により、DC Bend (5~10秒切り替え) に戻した。  
30秒切替で運転 (安全システムによる30秒待ち)。
  - Phase3からPulse-to-pulse運転予定

# A) Residual Dispersion in the BT line

- The dispersions have been corrected for each BT ARC one by one.
- After that dispersion of the BT overall was measured changing the beam energy.
- Non-negligible residual dispersion is still observed.**
- We should minimize  $\Delta \eta$  and  $\Delta \eta'$  at the end of BT.

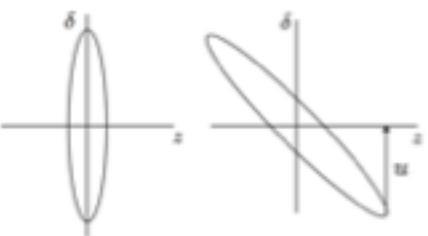
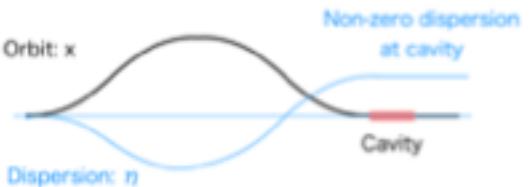


## 2. Improvements of emittance growth

### b. Residual dispersion at the acceleration structure for a compression system

- When the beam with dispersion is accelerated by RF cavity,  $\eta\delta$  converts to betatron oscillation and causes emittance growth.

M. Kikuchi



If the cavity has non-zero dispersion, a beam, gaining its energy depending on  $z$ , has net growth in the projected-emittance.

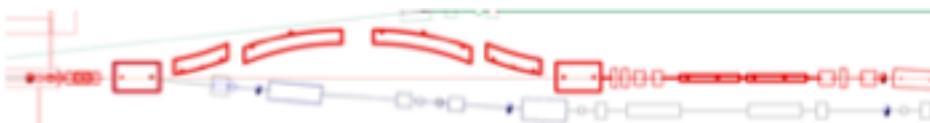
This is an analogue of the synchro-beta excitation at the cavity with non-zero dispersion in the ring.

$$\bar{\epsilon}^2 = \epsilon_0^2 + \epsilon_0 (\beta\eta'^2 + 2\alpha\eta\eta' + \gamma\eta^2) \langle u^2 \rangle$$

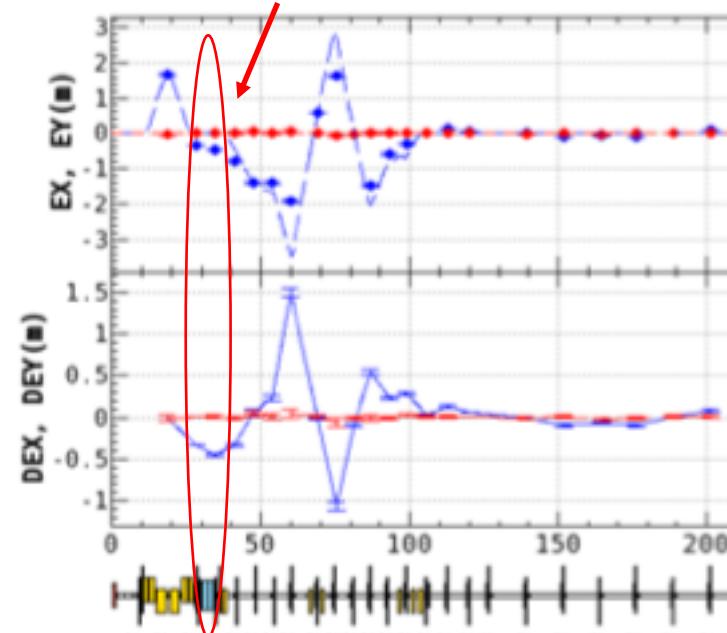
$$u = -vz \quad v = \frac{eV}{E_0} \frac{\omega_{rf}}{c}$$

Simulation result:  $\frac{\epsilon}{\epsilon_0} \sim 2$

ECS: Chicane+Acc



Measured dispersion from ECS at the end of LINAC.  
The dispersion is leak at the ECS cavity.

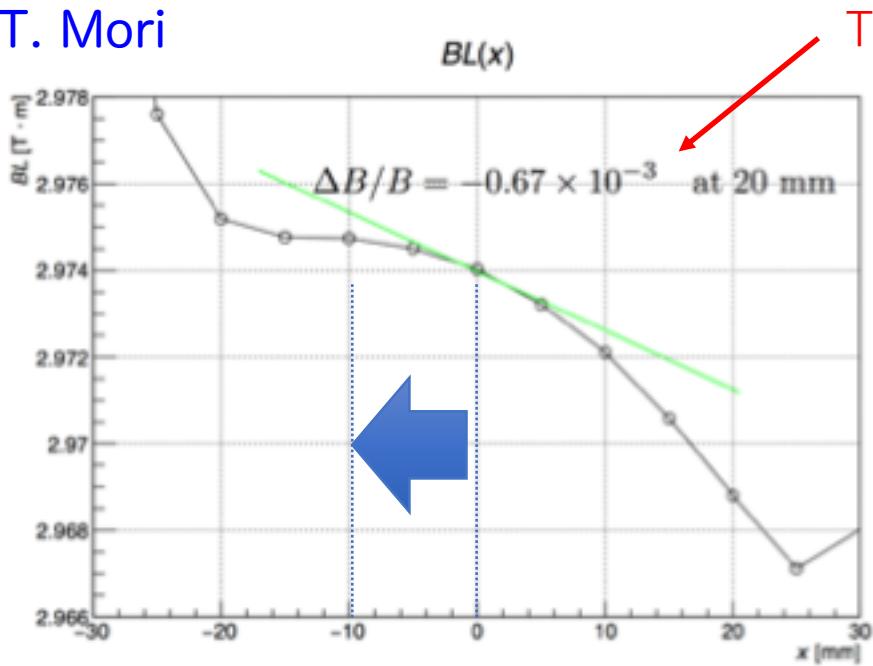


## 2. Improvements of emittance growth

### b. Residual dispersion at the acceleration structure for a compression system

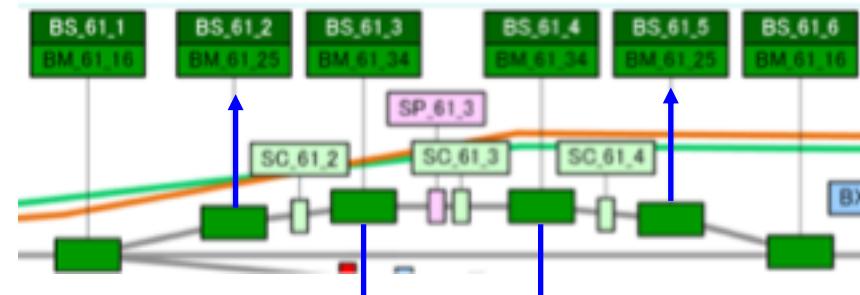
- The bending magnets used in ECS/SY3 have quadrupole component.
  - Passing through the design orbit in the bends, the beam feels  $B'$  field, which results in dispersion leakage.
  - By moving the bends about 10mm, the small area of  $B'$  can be passed.

T. Mori



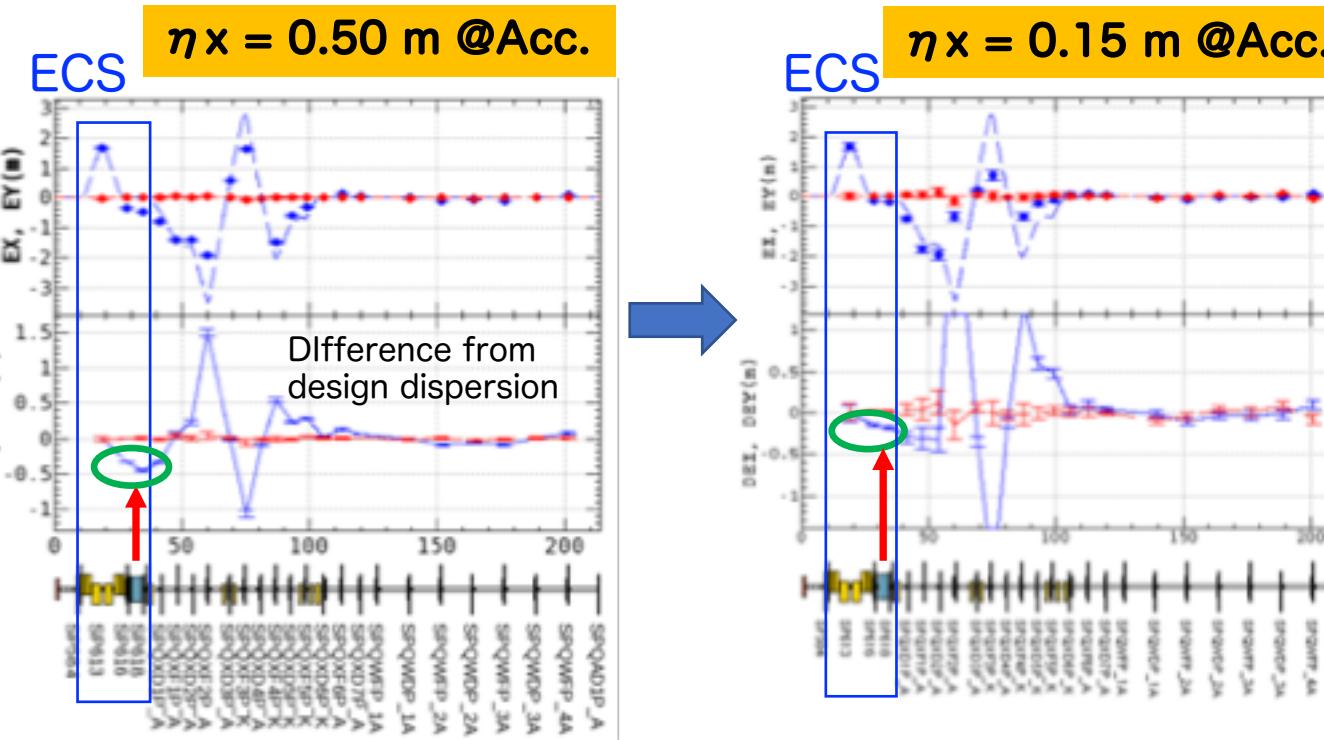
BL along the horizontal direction

This can explain the measured dispersion leak.



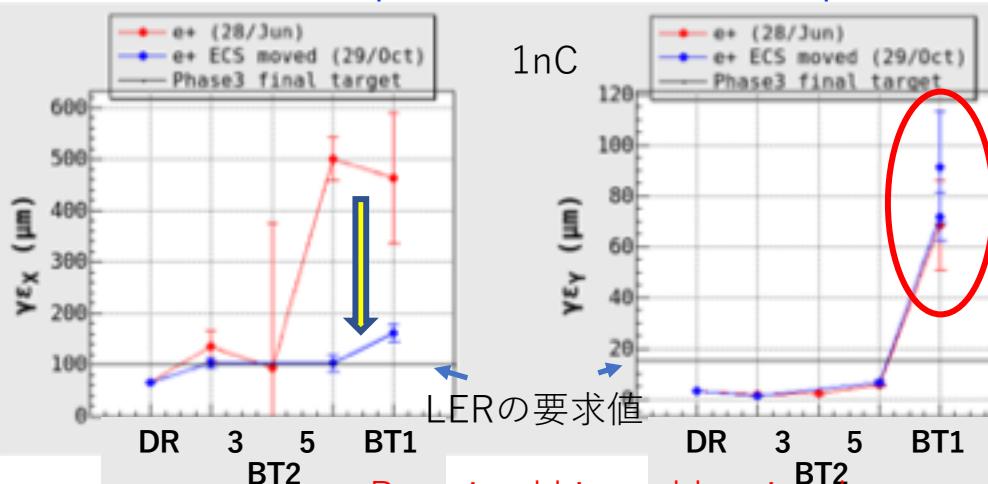
~10 mm

## 2. Improvements of emittance growth



Y. Seimiya

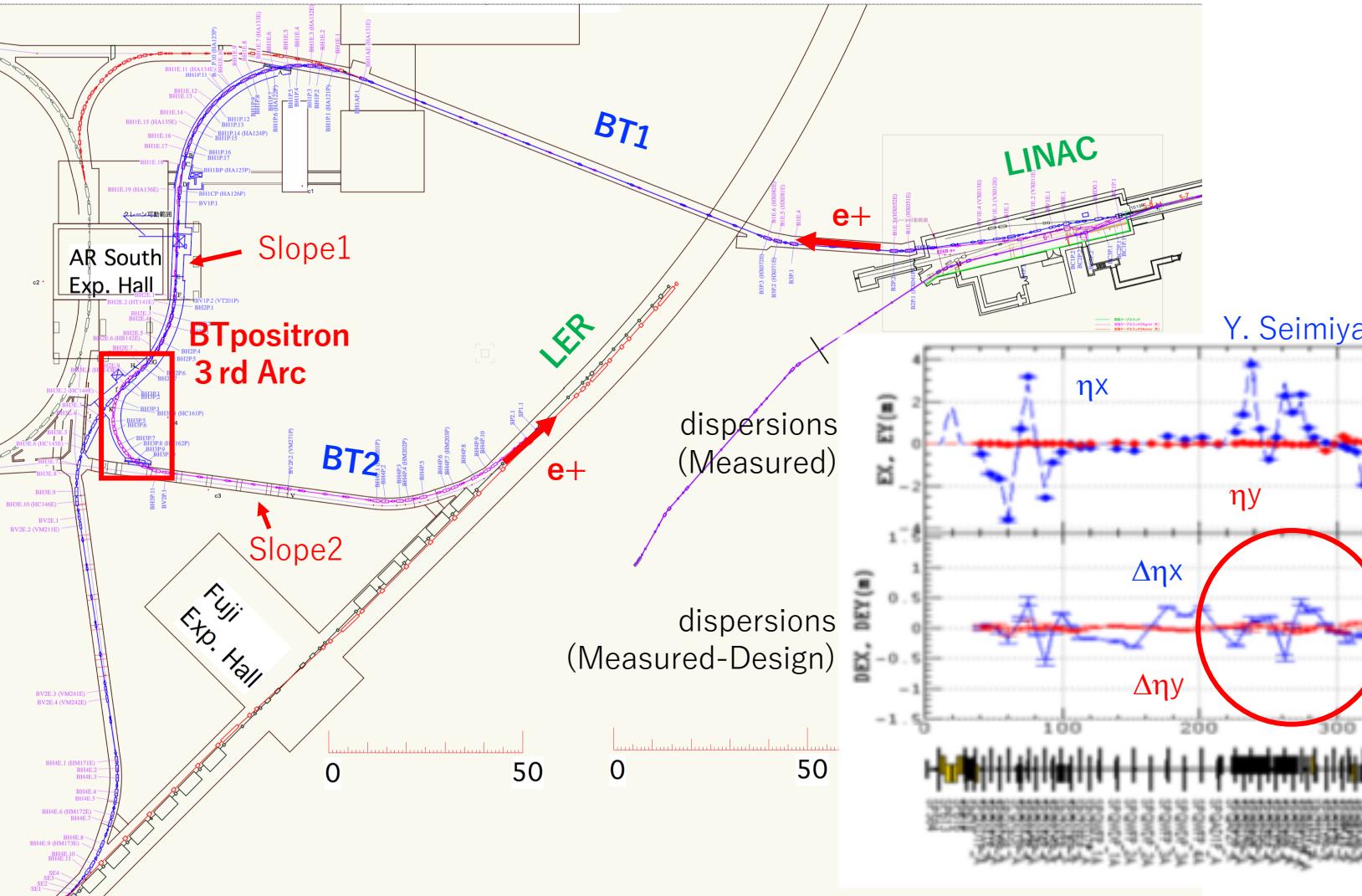
The horizontal dispersion has been improved by moving ECS bends.



Remained big problem is a large vertical emittance.  
This is considered to come from abnormal vertical dispersions.(M.)

## 2. Improvements of emittance growth

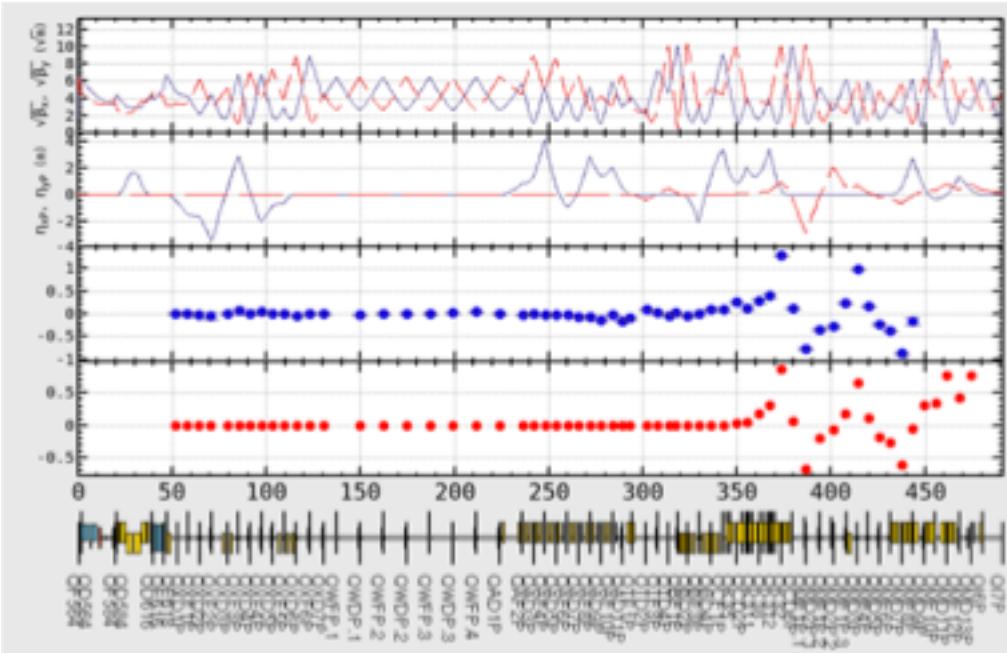
### B) Abnormal skew magnetic field from bends



# Simulation

M. Kikuchi

Kikuchi-san considered that the vertical dispersion could be corrected with the skew quads with permanent magnets.

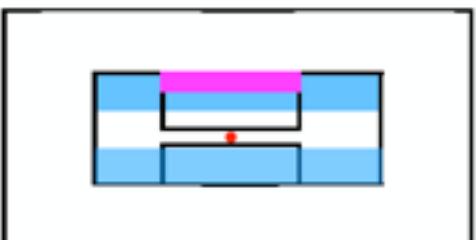


e+ beam

## Measured vertical dispersion before SkewQ

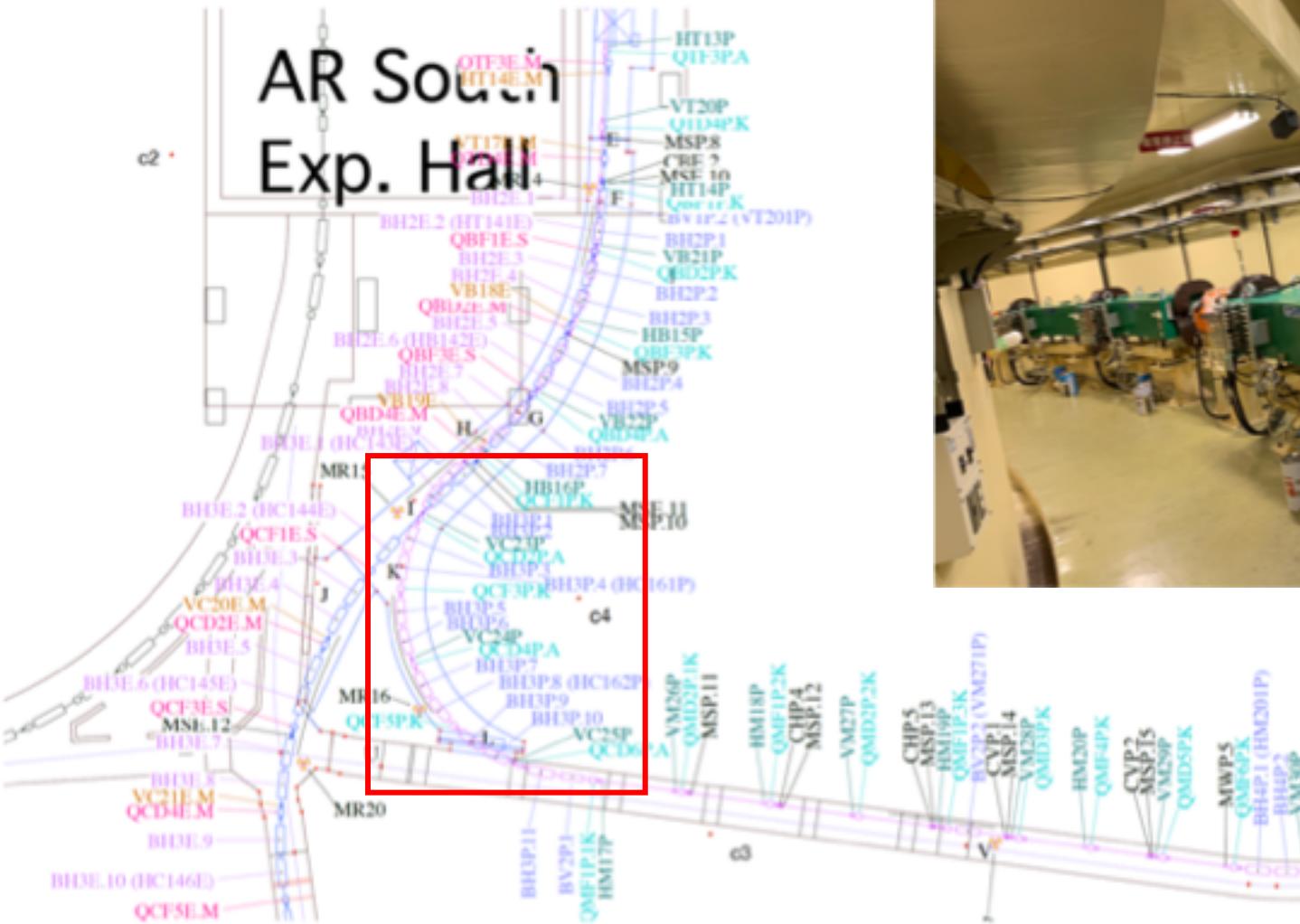
Calculated vertical dispersion by the SkewQ which are installed.

## Good agreement !

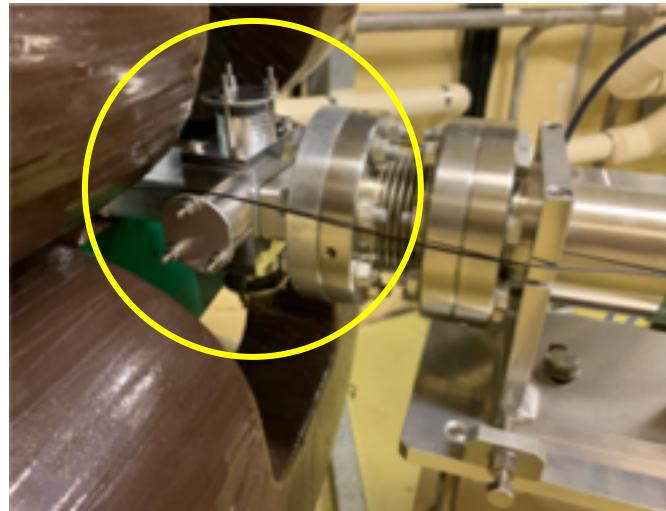
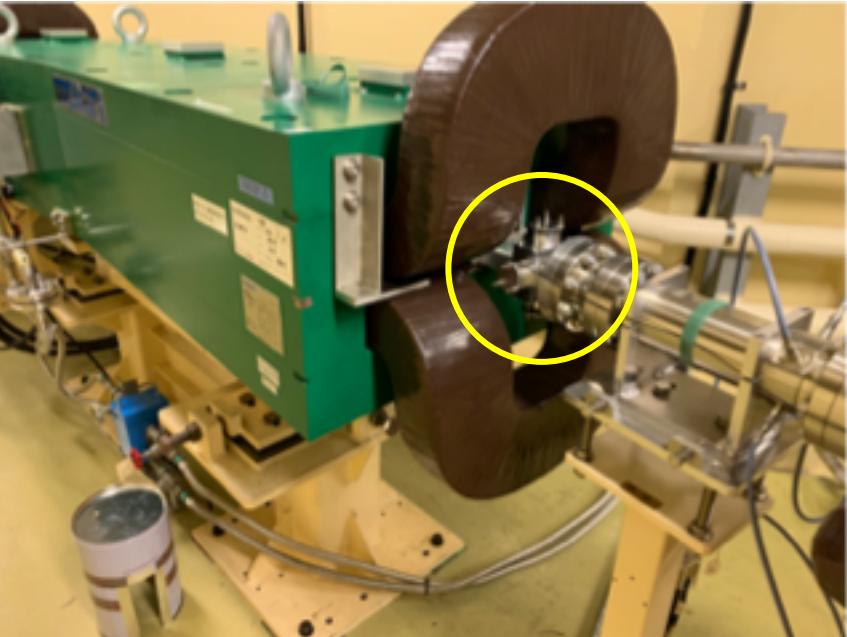


e+ビームのエネルギーが4GeVに上がったことにより、BendのGapを狭くした。このことがBendに異常なSkew成分を作った。しかし、このことは測定されたSkewQuad成分の約3分の一しか説明できない。とにかく、補正してみる。

## 2. Improvements of emittance growth



## 2. Improvements of emittance growth

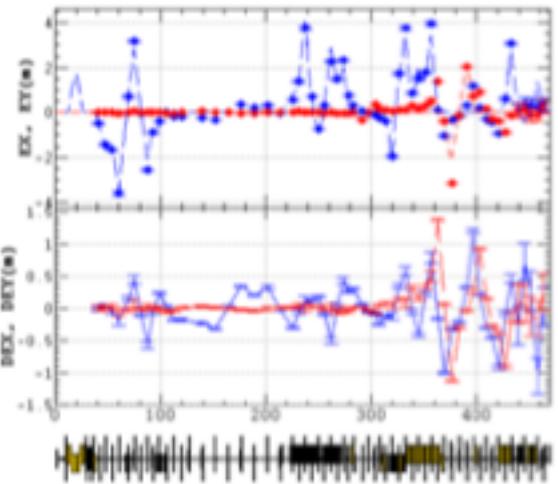


11 of 16 Skew Quads were installed.

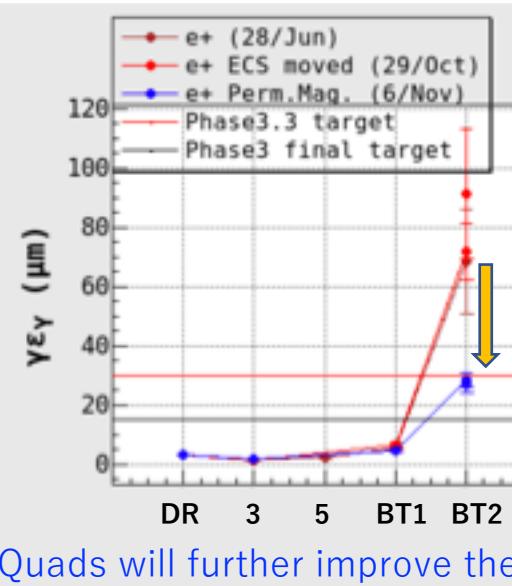
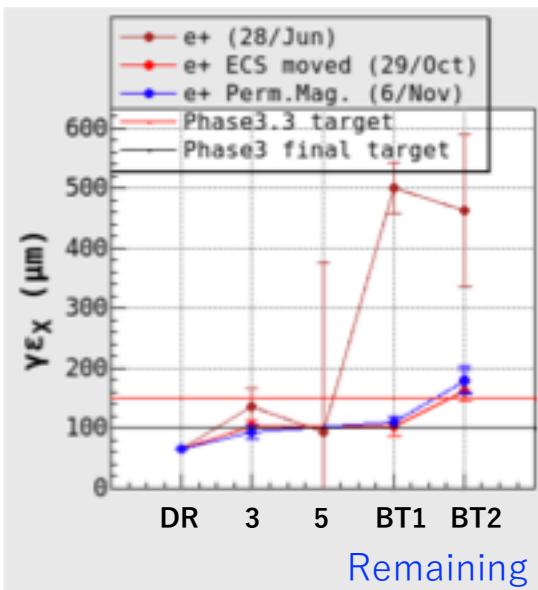
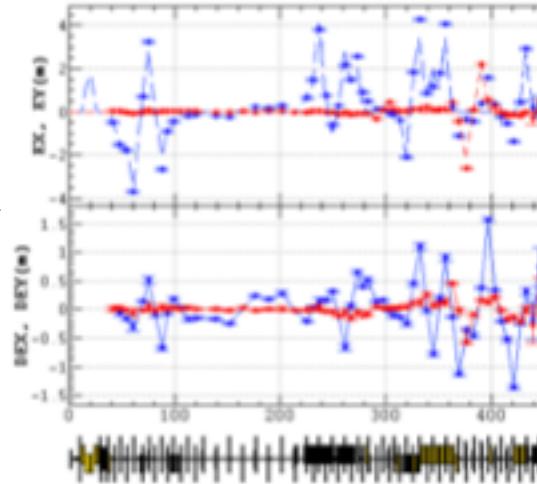
# Measured Dispersion

Y. Seimiya

① Before installation of skew quads

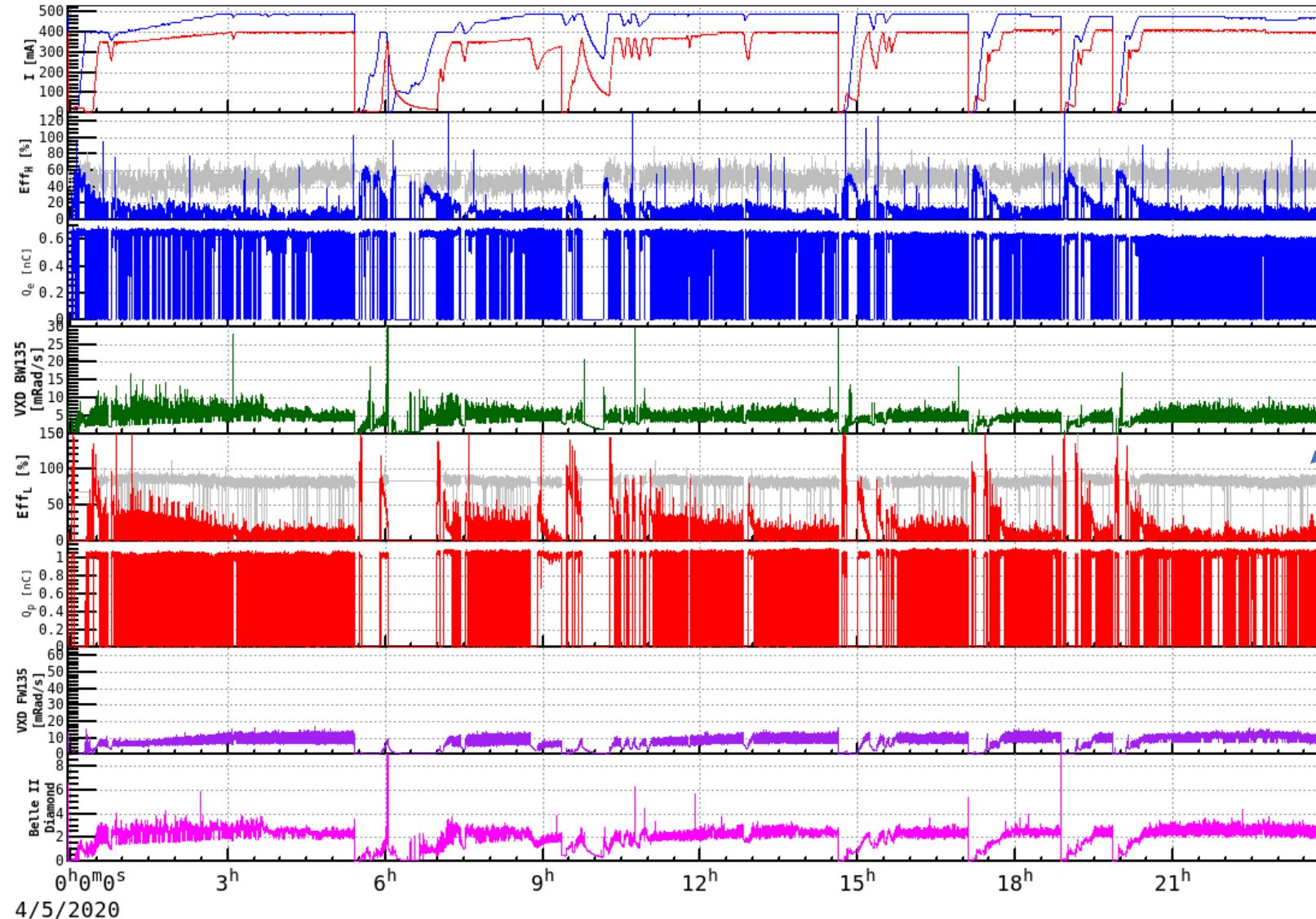


② After installation of skew quads



Remaining SkewQuads will further improve the vertical emittance.

# 生の入射効率 (MRのビーム寿命によらない)



Bunch current monitorから計算した入射後数ms後の入射効率